

**Kinetics-Controlled Composition Profile
of
Semiconductor Alloy Quantum Dots and Nanowires
via
Growth Mode**

Feng Liu

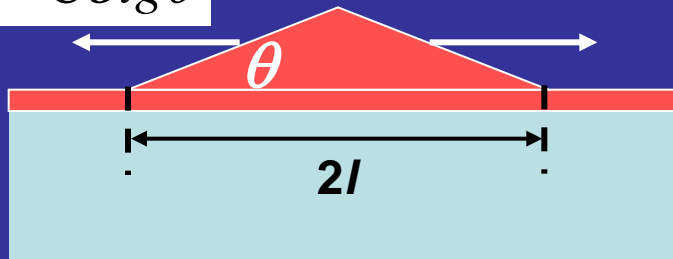
in Collaboration with Xiaobin Niu and **Gerald B. Stringfellow**

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University of Utah

Support: DOE-BES, CAO Group

Island Nucleation on a Flat Surface

$$f = C\varepsilon \operatorname{tg} \theta$$

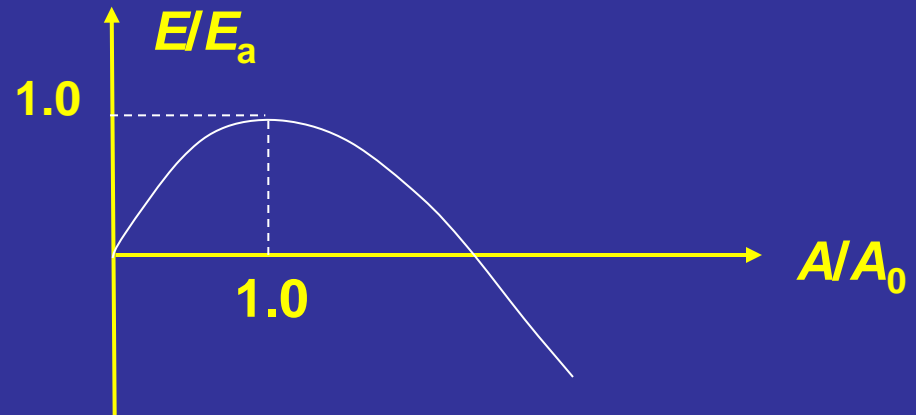


$$E = 2\Gamma A^{1/2} \operatorname{tg}^{1/2} \theta - (3/2)\varepsilon_0 A \operatorname{tg} \theta$$

$$\varepsilon_0 = c\varepsilon^2; \quad \Gamma = (\gamma_f \sec \theta - \gamma_w)(\operatorname{tg} \theta)^{-1}$$

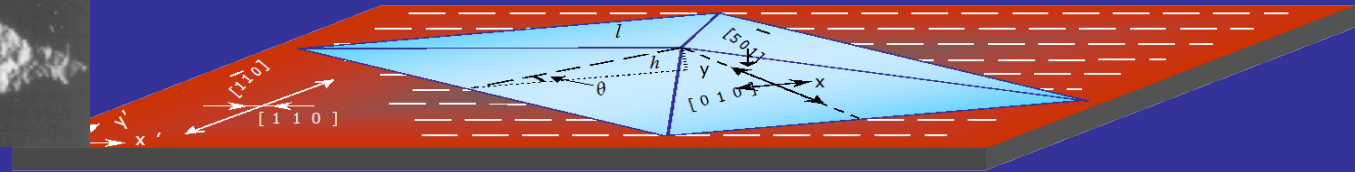
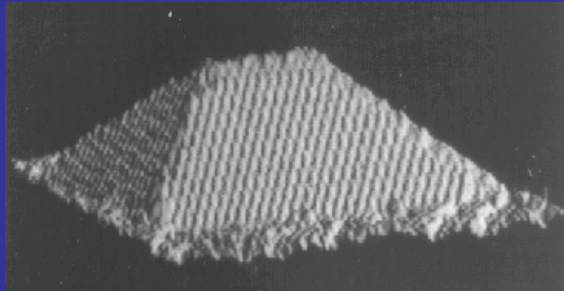
$$A_0 = (4/9)(\Gamma / \varepsilon_0)^2 (\operatorname{tg} \theta)^{-1}$$

$$E_a = (2/3)(\Gamma^2 / \varepsilon_0)$$



3D solution:
$$E = 4\Gamma V^{2/3} \operatorname{tg}^{1/3} \theta - 6C\varepsilon^2 V \operatorname{tg} \theta$$

(105)-faceted Ge Dot on Si(001)



$$E = 4\Gamma V^{2/3} \tan^{1/3} \theta - 6cV \tan \theta - 8C' V^{1/3} \cot^{1/3} \theta \ln(2V^{1/3} \cot^{1/3} \theta / a)$$

$$\Gamma = \gamma_h \csc \theta - \gamma_w \cot \theta$$

$$V \approx h^3 \cot^2 \theta$$

$$c = (M_{Ge} \varepsilon)^2 (1 - \nu) / 2\pi G_{Si}$$

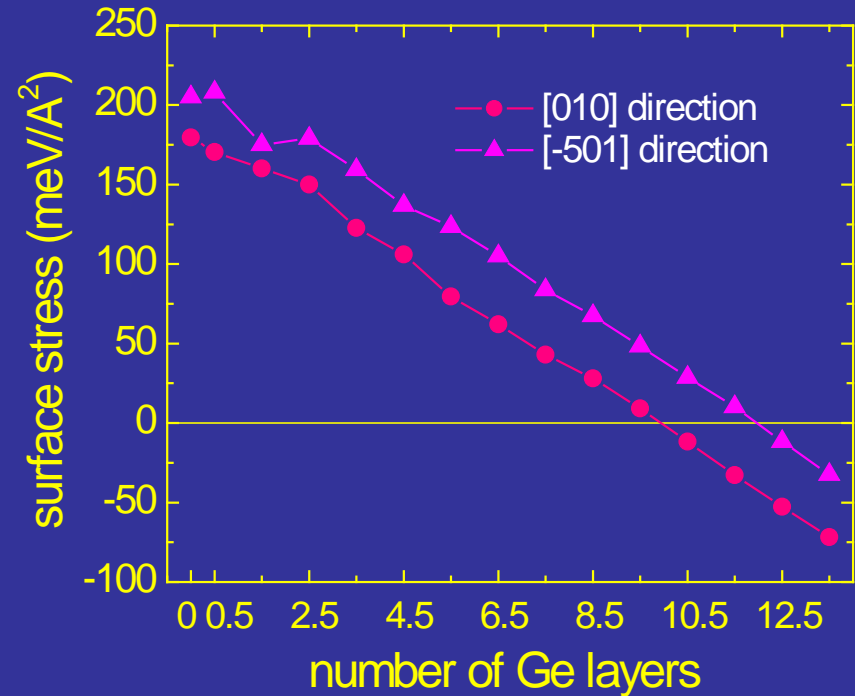
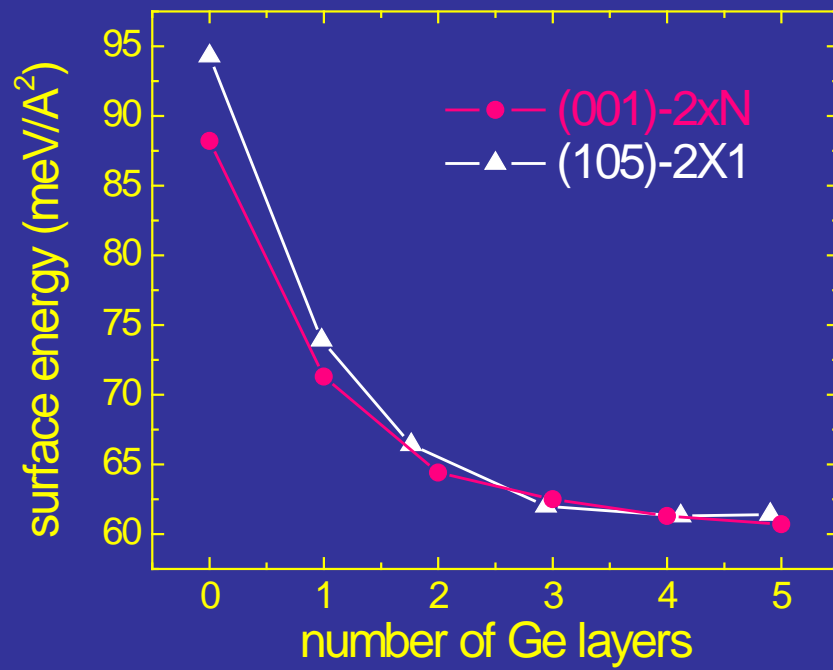
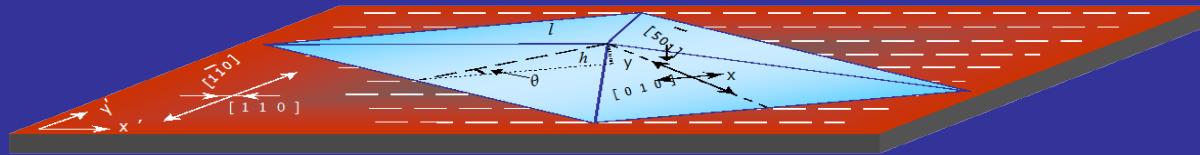
$$c' = F_{\perp}^2 (1 - \nu) / 2\pi G_{Si}$$

γ_h : converged Ge/Si(105) surface energy

γ_w : Ge/Si (001) surface energy of 4 and 5 layers Ge deposition

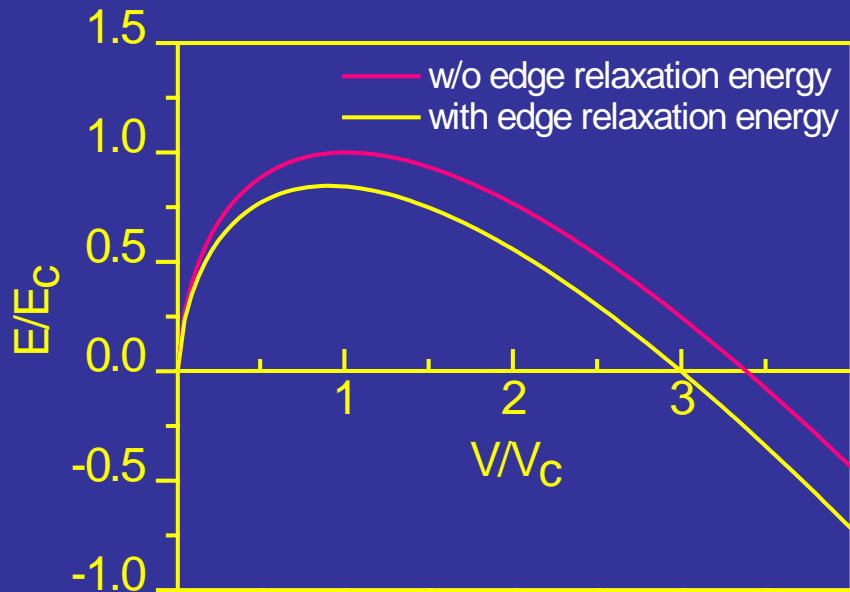
$$F_{\perp} = \sigma_{xx}^h \cdot \cos \theta - \sigma_{xx}^w$$

First-principles: Surface Energy/Stress



PRL, 94, 176103 (05); PRB 72, 125415 (05)

Quantitative Prediction: Critical Size/stability (first-principles + continuum)



$$h_c \approx 4\Gamma / 9c$$

$$h_c \sim \varepsilon^{-2}$$

Pure Ge hut:

$$h_c \sim 16\text{\AA}; 6800 \text{ atoms}$$

25% Ge SiGe alloy hut:

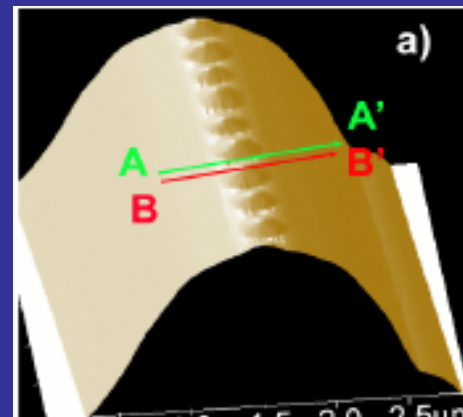
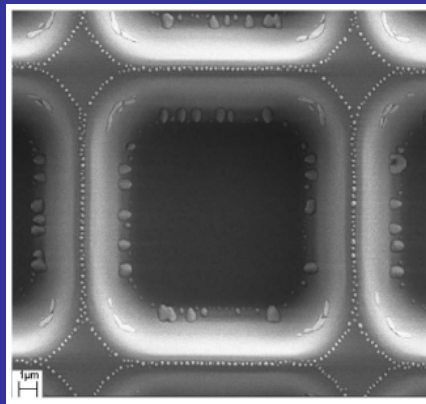
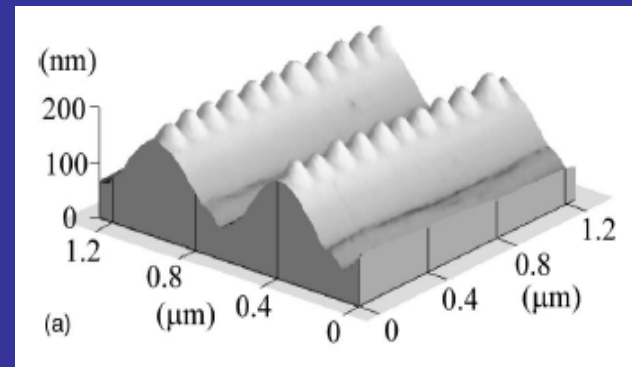
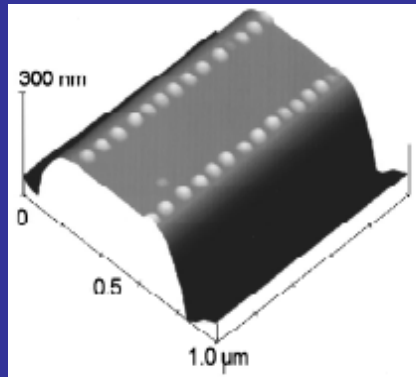
$$h_c \sim 216\text{\AA}; 2.3 \times 10^7 \text{ atoms}$$

Implication on formation mechanism:

- too large via nucleation
- non-faceted "pre-pyramids"

(continuum mounds or stepped islands)

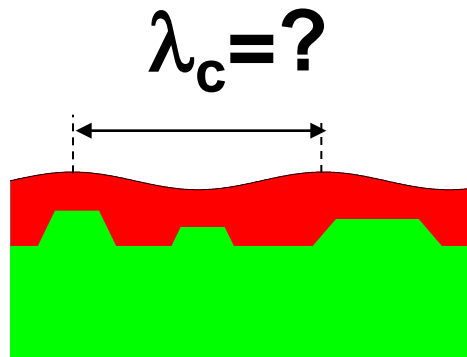
Directed Self-Assembly of Strained Islands on Patterned Substrate



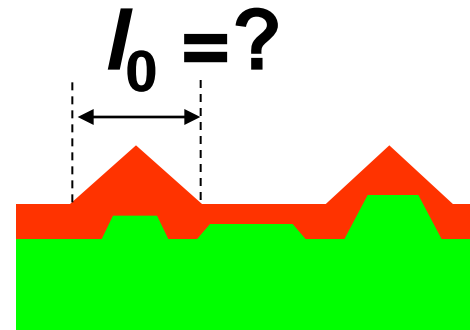
Kamins and Williams, APL 71, 1201 (97); Jin, *et al.*, APL 75, 2752 (99);
Zhong, *et al.*, APL 82, 445 (03); Yang, *et al.*, PRL 92, 0255502 (04).

Morphological Instability on Patterned Substrate?

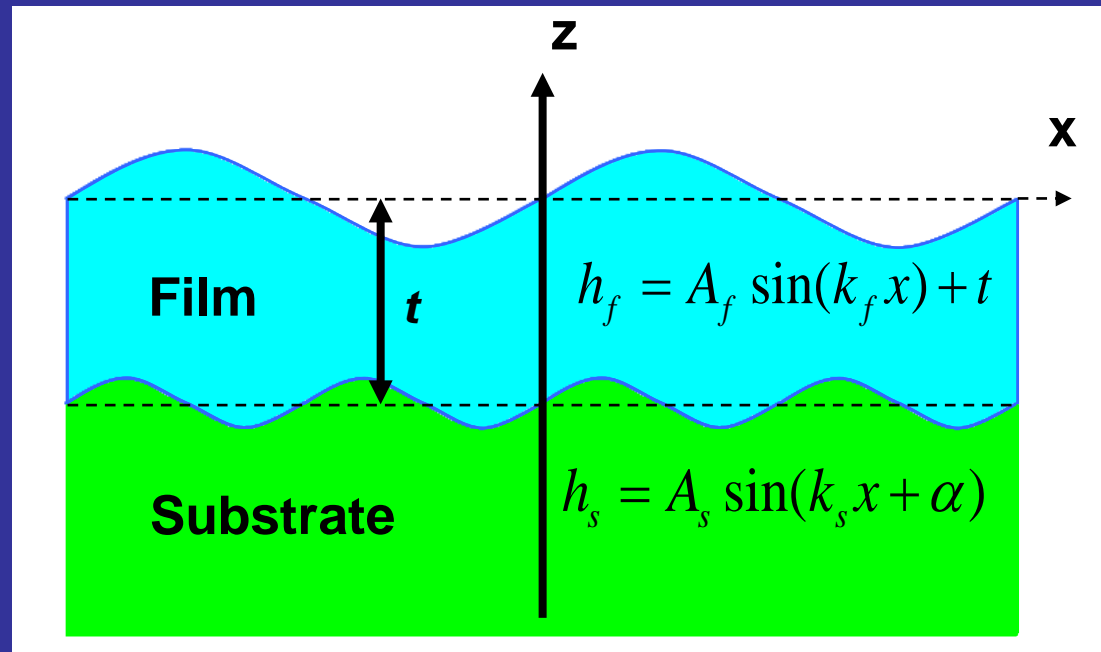
Surface undulation



Island formation



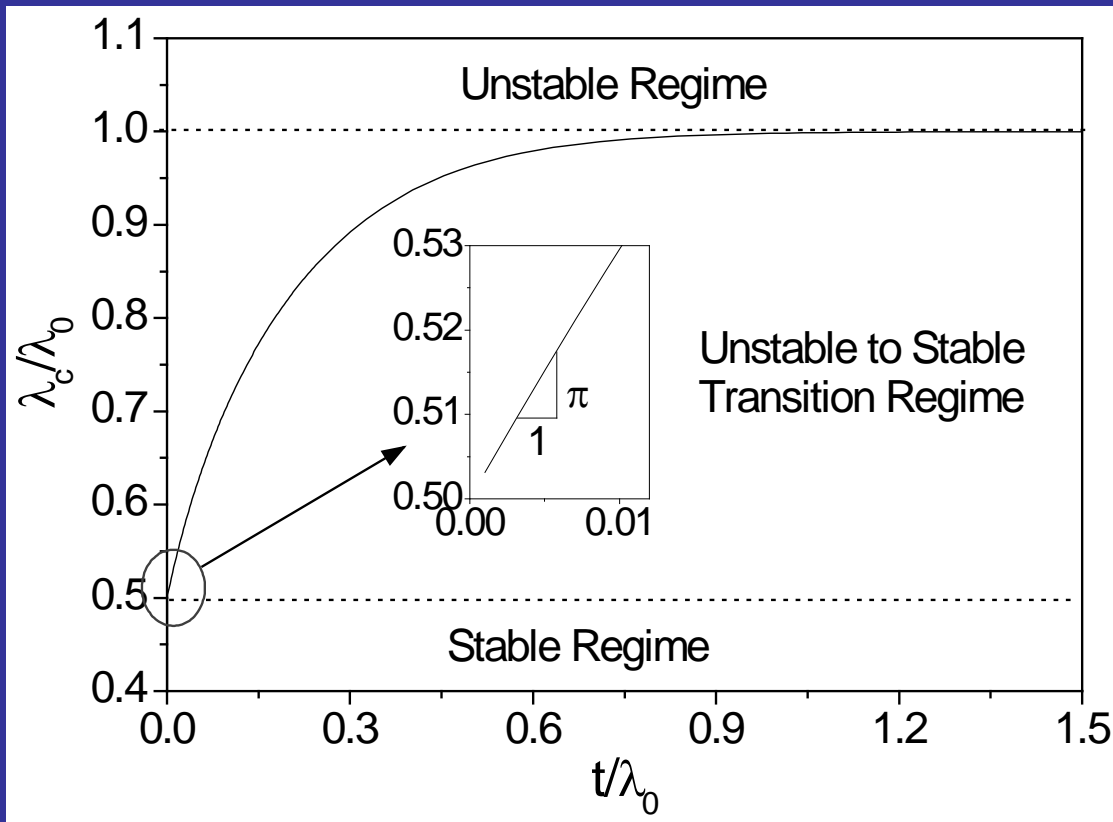
Critical Wavelength on a Wavy Substrate



$$\sigma_{xx} = \sigma - 2\sigma A_f k_f \sin(k_f x) + 2\sigma A_s k_s e^{-k_s t} \sin(k_s x + \alpha)$$

$$\lambda_c (1 + e^{-2\pi t / \lambda_c}) = \lambda_0$$

Dependence of Critical Wavelength on Film Thickness



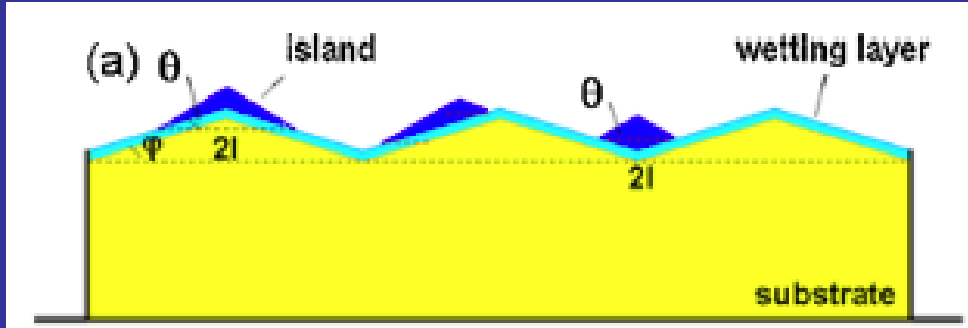
$$\lambda_c (1 + e^{-2\pi t/\lambda_c}) = \lambda_0$$

$$t \rightarrow 0, \lambda_c \rightarrow \lambda_0 / 2$$

$$t \ll 1, \lambda_c \cong \lambda_0 / 2 + \pi t$$

$$t \rightarrow \infty, \lambda_c \rightarrow \lambda_0$$

Island Nucleation on Faceted Surface



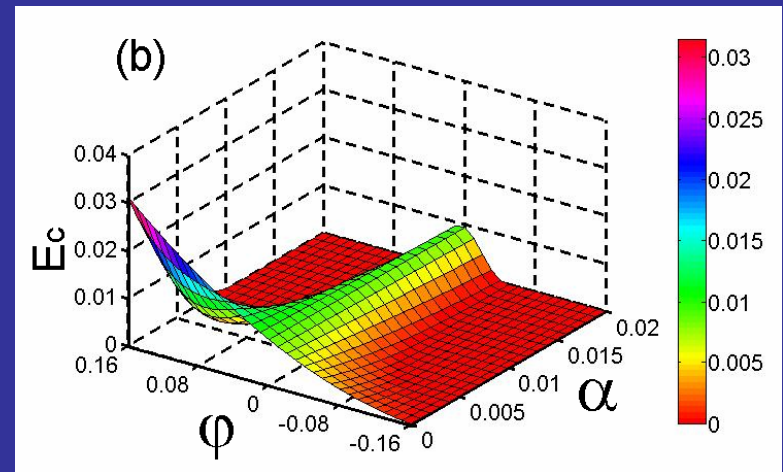
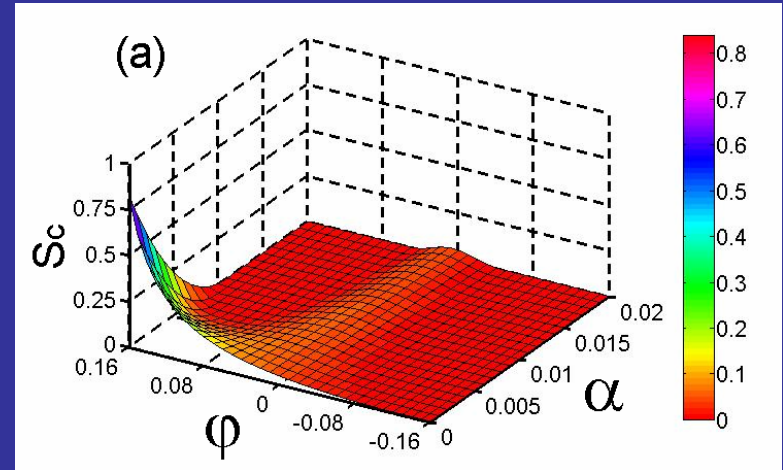
$$E = -\varepsilon_0 S (\tan \theta - \tan \varphi) + 2\Gamma S^{1/2} (\tan \theta - \tan \varphi)^{1/2}$$

$$S_c = (\Gamma / \varepsilon_0)^2 (\tan \theta - \tan \varphi)^{-1}$$

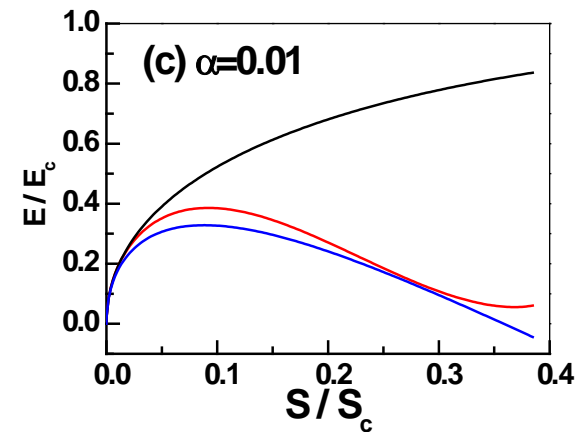
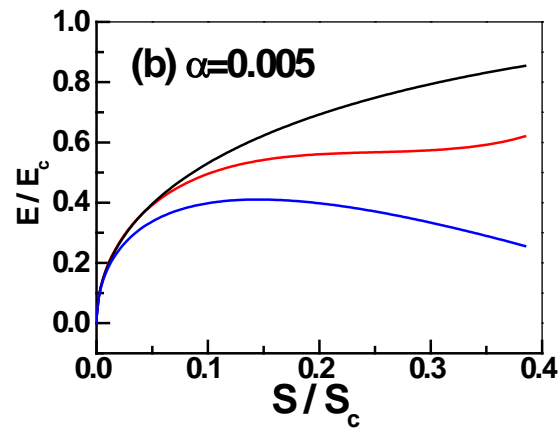
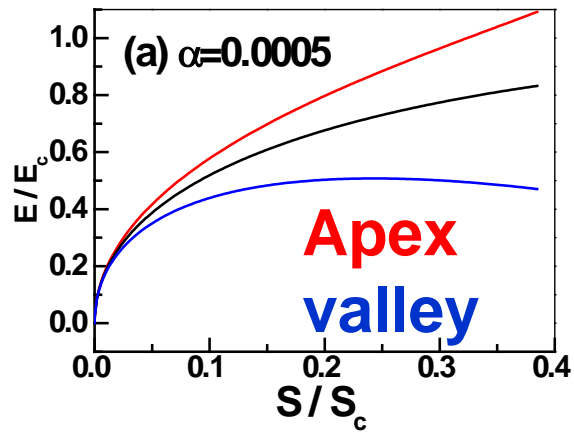
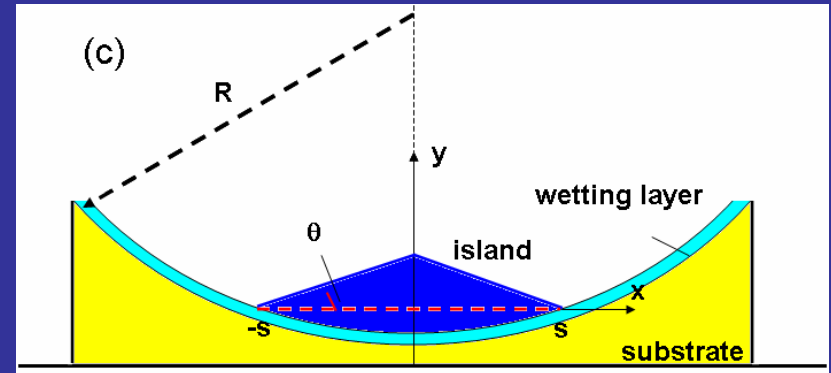
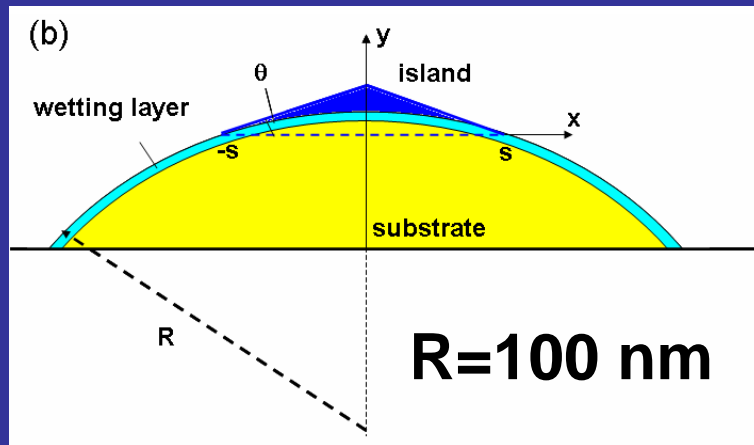
$$E_c = \Gamma^2 / \varepsilon_0$$

$$\Gamma = (\gamma_f \sec \theta - \gamma_w \sec \varphi) (\tan \theta - \tan \varphi)^{-1}$$

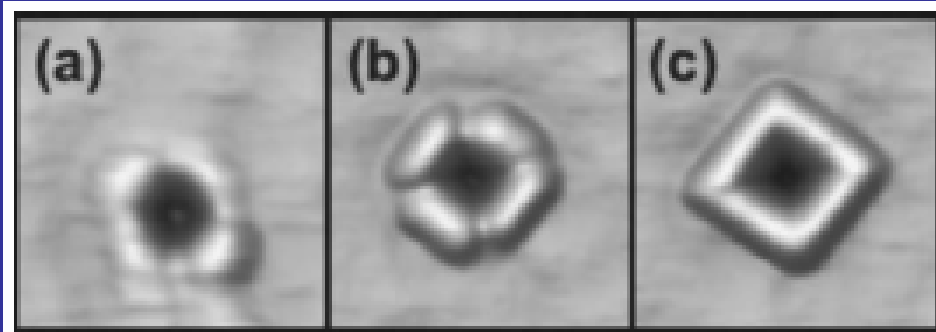
$$\gamma = \gamma_0 [1 - \alpha \cos(n\varphi)]$$



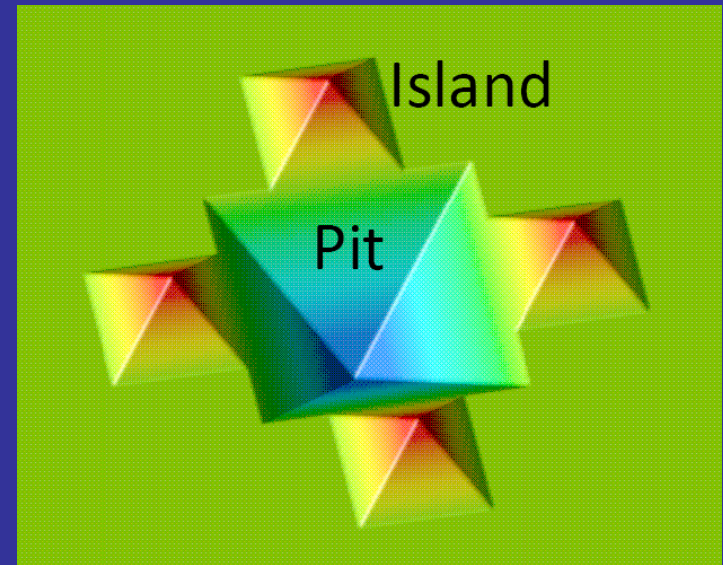
Island Nucleation on Curved Surface



Heterogeneous Nucleation of QDMs



Gray et al. PRB 72,155323(05)



$$E = (4\Gamma V^{2/3} \tan^{1/3} \theta - 6\varepsilon_0 V) + E_{pi} + E_{ii1} / 2 + E_{ii2}$$

$\varepsilon_0 = \sigma^2(1-\nu^2)/\pi Y$ is the strain energy density,

$\Gamma = \gamma(\sec\theta - 1)\tan^{-1}\theta$ is reduced surface energy density.

E_{pi} is the strain interaction energy between pit and island.

E_{ii1} is the strain interaction energy between two opposite islands.

E_{ii2} is the strain interaction energy between two adjacent islands.

$$E_{pi} = -\frac{16\epsilon_0 V_p \cdot V_i}{3 \cot \theta (V_p^{1/3} + V_i^{1/3})^3}$$

$$E_{ii1} = \frac{2\epsilon_0 V_i^2}{3 \cot \theta (V_p^{1/3} + V_i^{1/3})^3} \quad E_{ii2} = \frac{4\sqrt{2}\epsilon_0 V_i^2}{3 \cot \theta (V_p^{1/3} + V_i^{1/3})^3}$$

Setting:

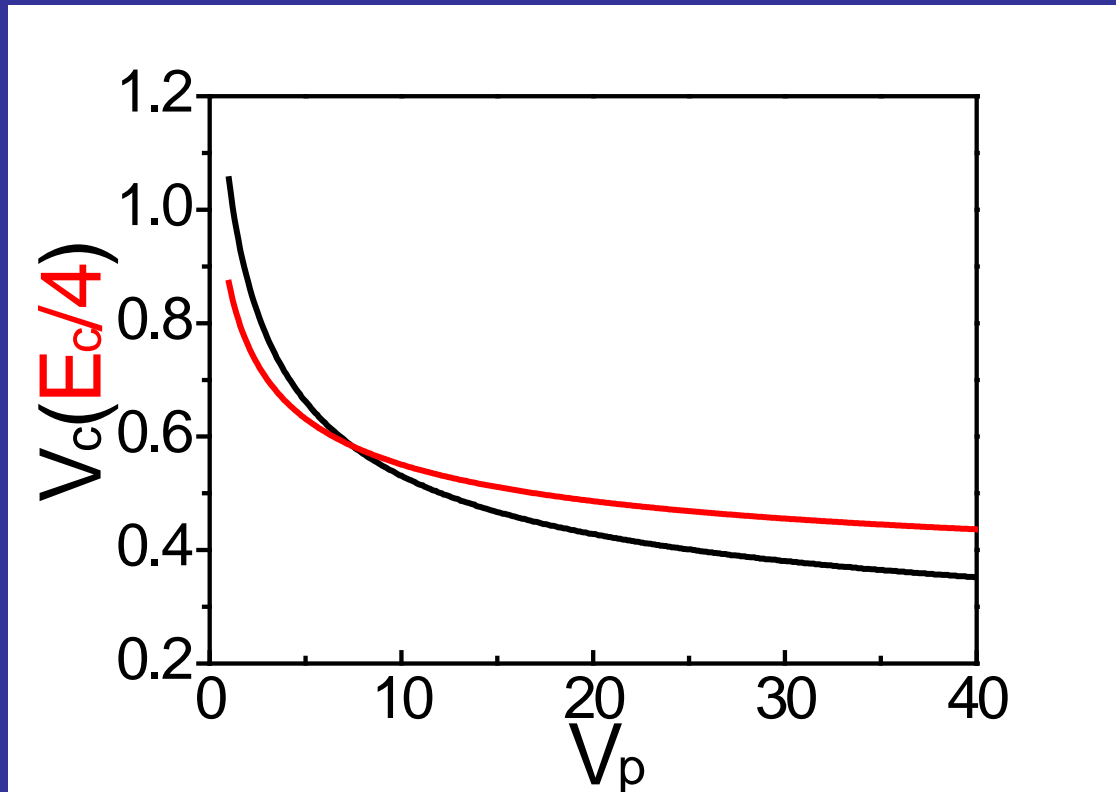
$$E_c^0 = \frac{1}{3} \frac{(4\Gamma)^3}{(9\epsilon_0)^2} \cot \theta$$

$$V_c^0 = \left(\frac{4\Gamma}{9\epsilon_0} \right)^3 \cot^2 \theta$$

$$E = (3V_i^{2/3} - 2V_i) - \frac{16V_p \cdot V_i}{9(V_p^{1/3} + V_i^{1/3})^3} + \frac{V_i^2}{9(V_p^{1/3} + V_i^{1/3})^3} + \frac{4\sqrt{2}V_i^2}{9(V_p^{1/3} + V_i^{1/3})^3}$$

in units of E_0^c and V_0^c

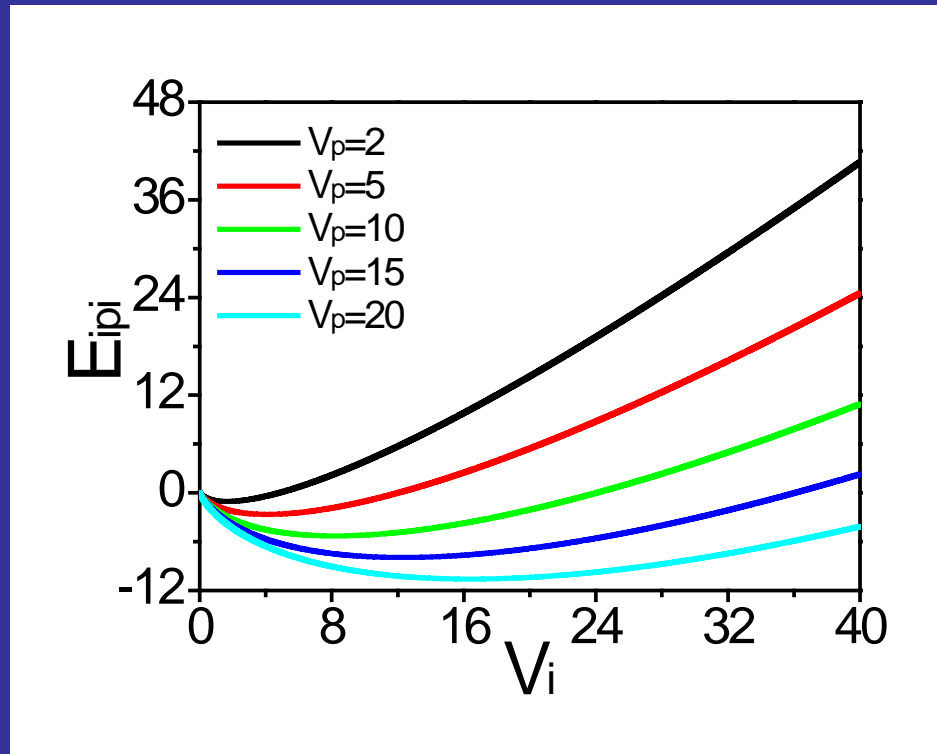
Nucleation Barrier and Critical Size of QDMs



Islands prefer to nucleate next to a pit to form QDM.

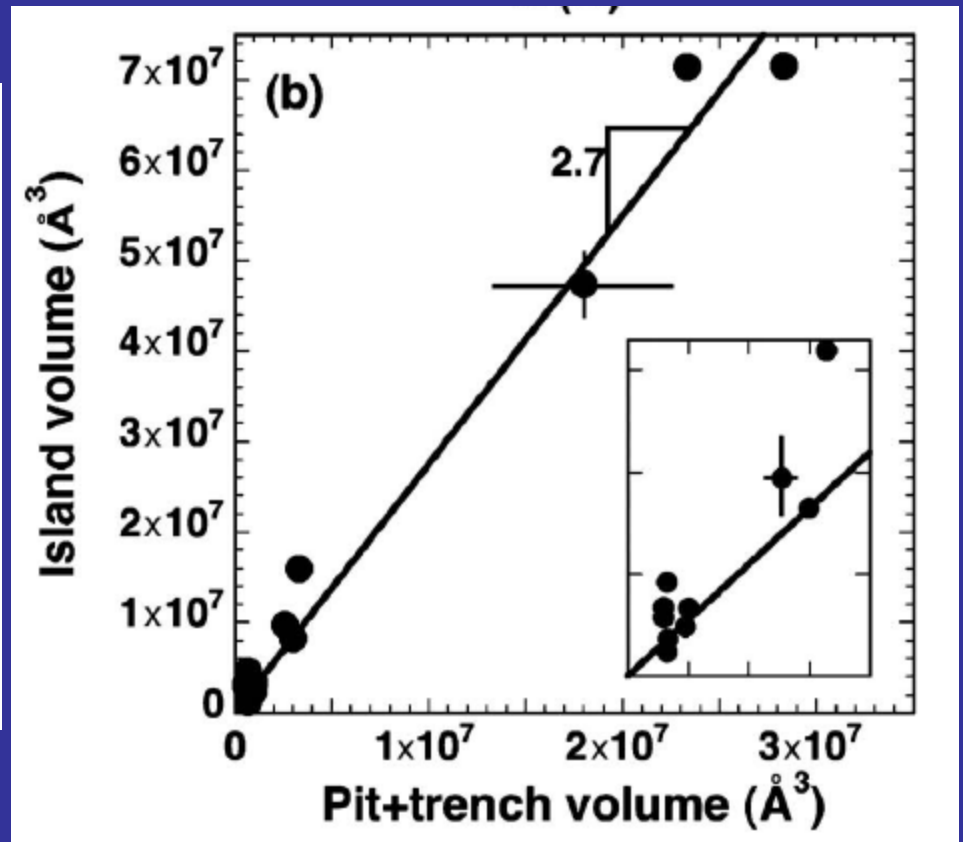
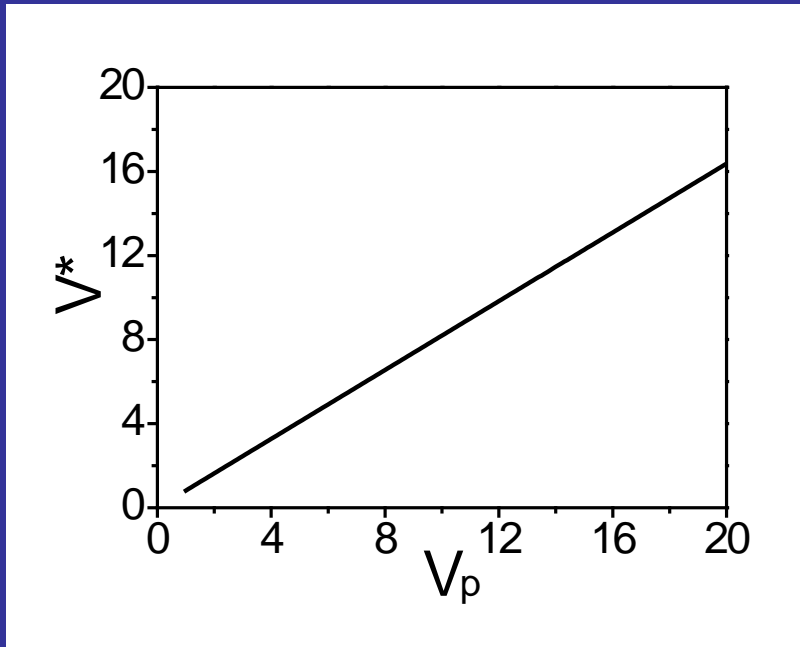
Self-Limited Growth

$$E_{ipi} = -\frac{16V_p \cdot V_i}{9(V_p^{1/3} + V_i^{1/3})^3} + \frac{V_i^2}{9(V_p^{1/3} + V_i^{1/3})^3} + \frac{4\sqrt{2}V_i^2}{9(V_p^{1/3} + V_i^{1/3})^3}$$

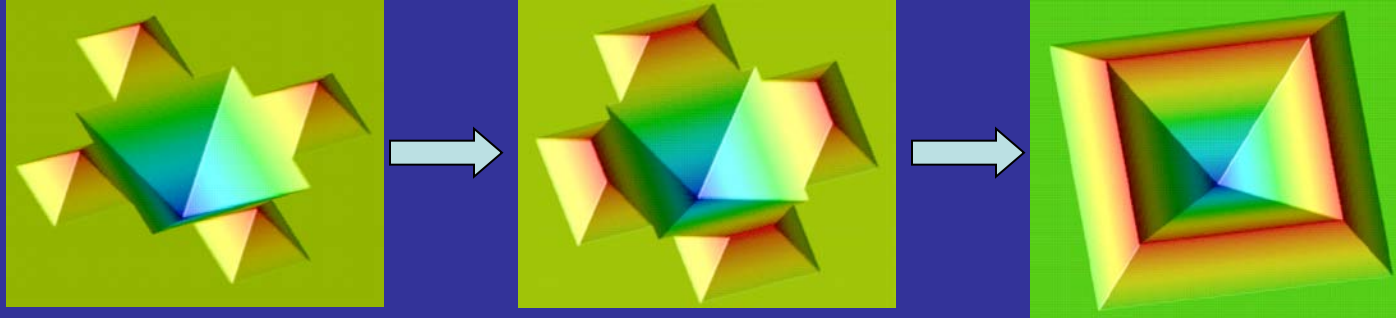


Critical volume V^* at minimum E_{ipi}

V^* vs. V_p : linear



Island Elongation



$$E = -2[s \ln et + t \ln es] - \frac{\frac{8}{3} l_p^3 \left(st + \frac{1}{3} e^{1 - \frac{2\Gamma}{\varepsilon_0 h}} \right)}{\left(l_p + \frac{s + e^{\frac{1 - \Gamma}{2 \varepsilon_0 h}}}{2} \right)^2 e^{\frac{1 - \Gamma}{2 \varepsilon_0 h}}} + \frac{(1 + 4\sqrt{2}) \left(st + \frac{1}{3} e^{1 - \frac{2\Gamma}{\varepsilon_0 h}} \right)^2}{16 \left(l_p + \frac{s + e^{\frac{1 - \Gamma}{2 \varepsilon_0 h}}}{2} \right)^2}$$

A Simple Theoretical Model

predicting the effect of strain on surface diffusion

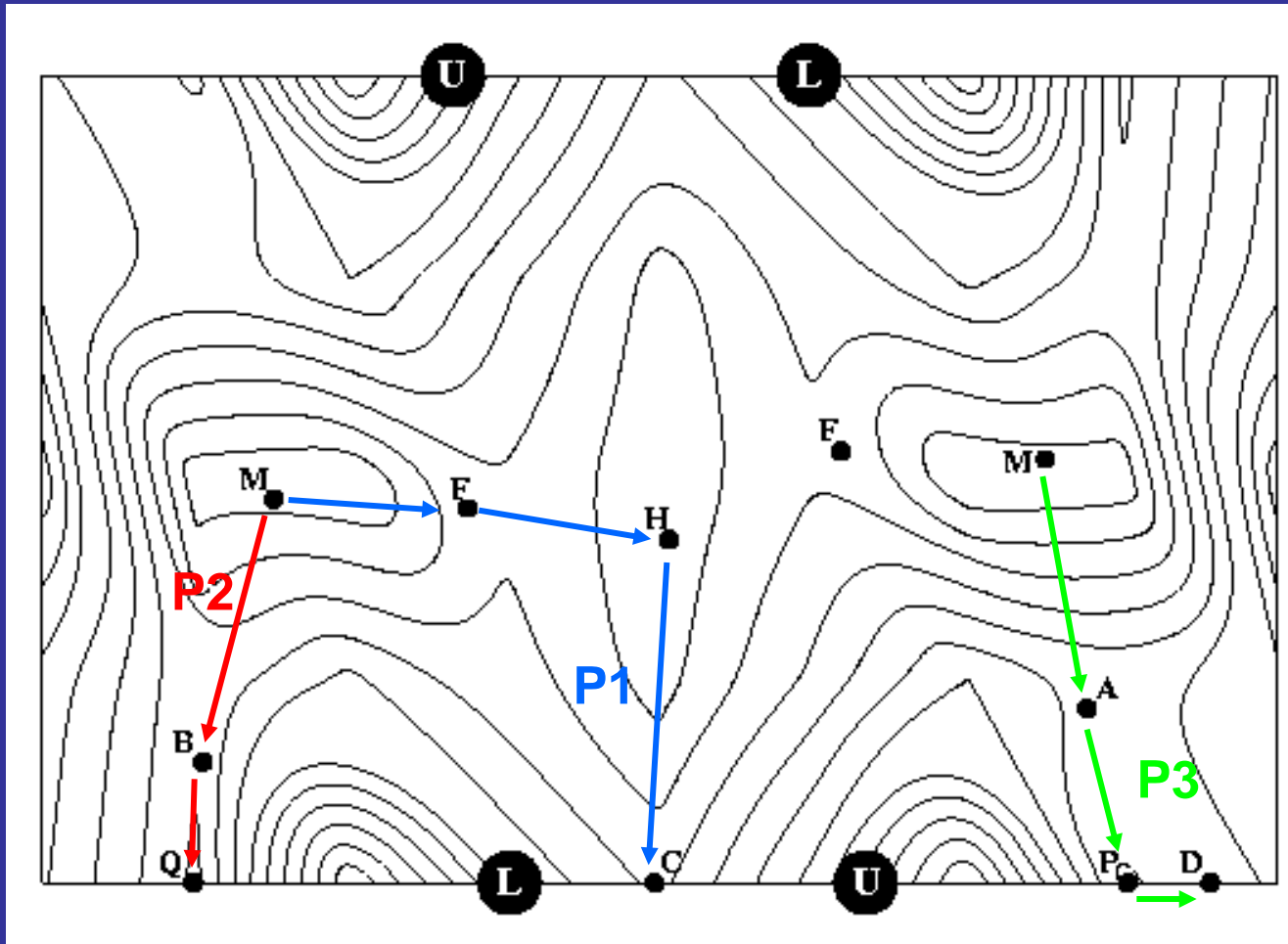


$$E_b^0 = E_s - E_m$$

$$\begin{aligned} E_b(\varepsilon) &= (E_s - E_m) + A(\sigma_s - \sigma_m)\varepsilon \\ &= E_b^0 + A(\Delta\sigma)\varepsilon \end{aligned}$$

- Calculating adatom-induced surface stress on “unstrained surface”

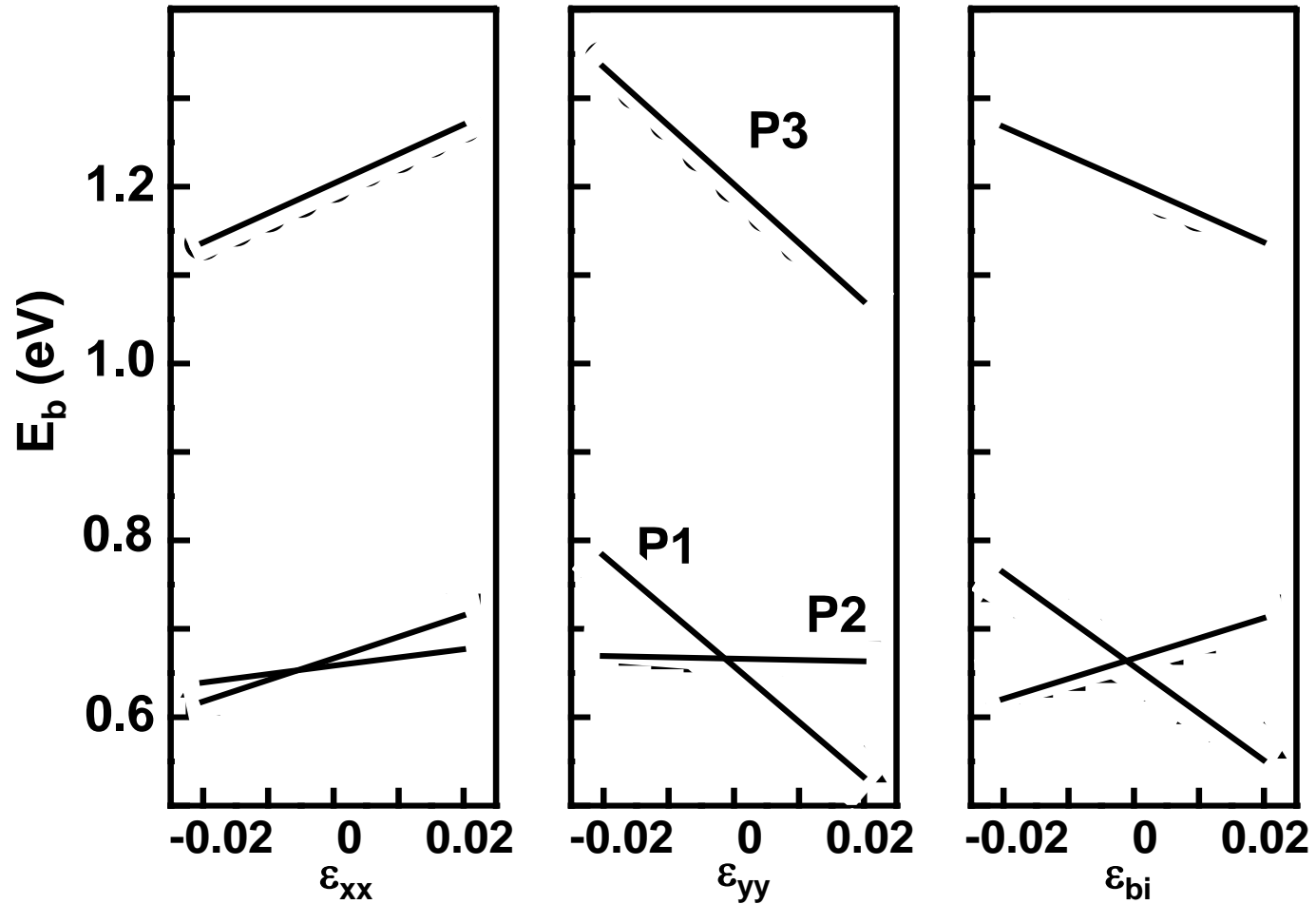
Potential-energy Surface on Unstrained Si(001) Surface



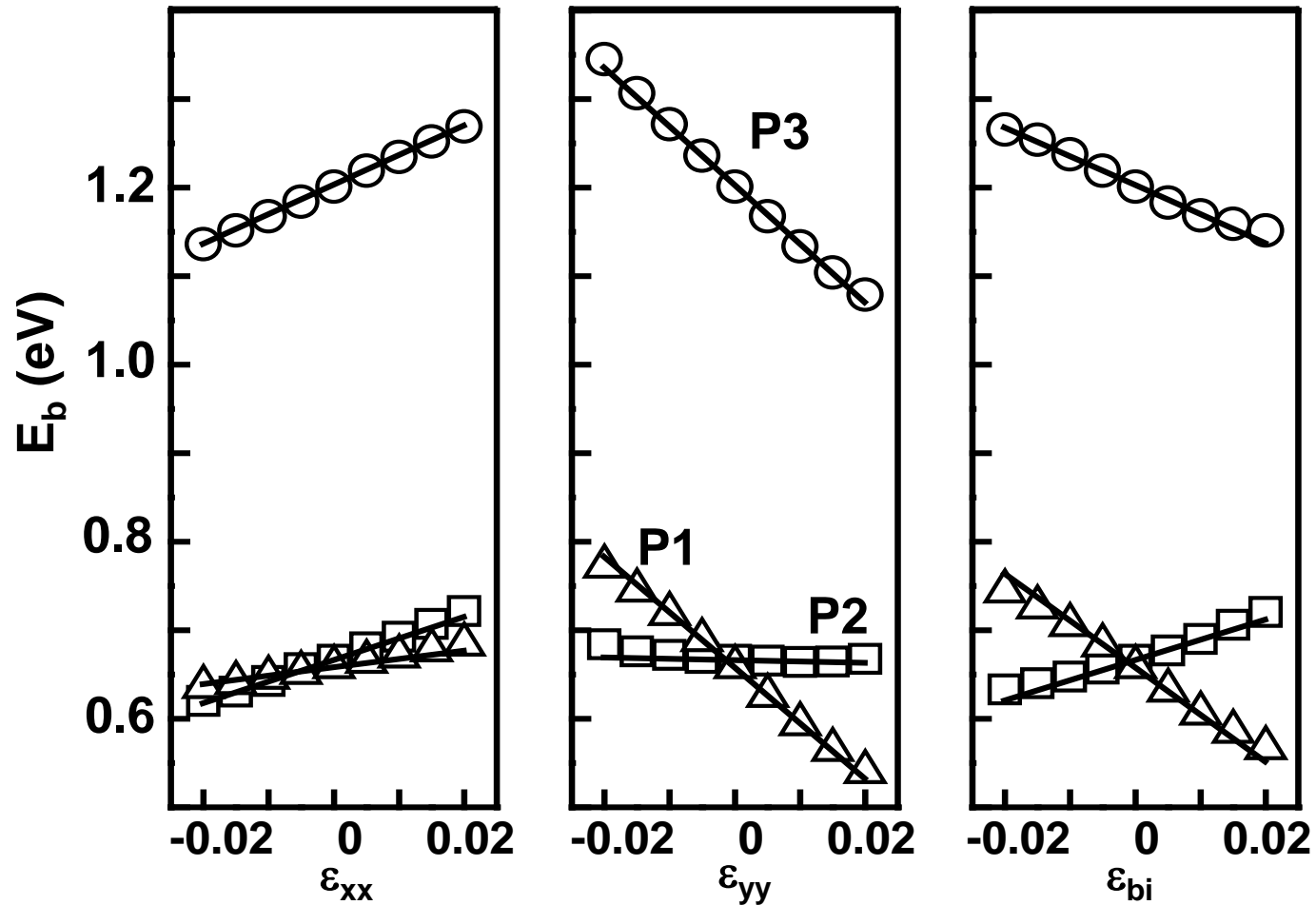
Adatom Diffusional Stress

	P1	P2	P3
$A(\Delta\sigma_{xx})$	0.94	2.43	3.32
$A(\Delta\sigma_{yy})$	-6.23	-0.15	-6.60
$A(\Delta\sigma)$	-5.29	2.28	-3.28

Predicted Dependence of Diffusion Barrier on Strain

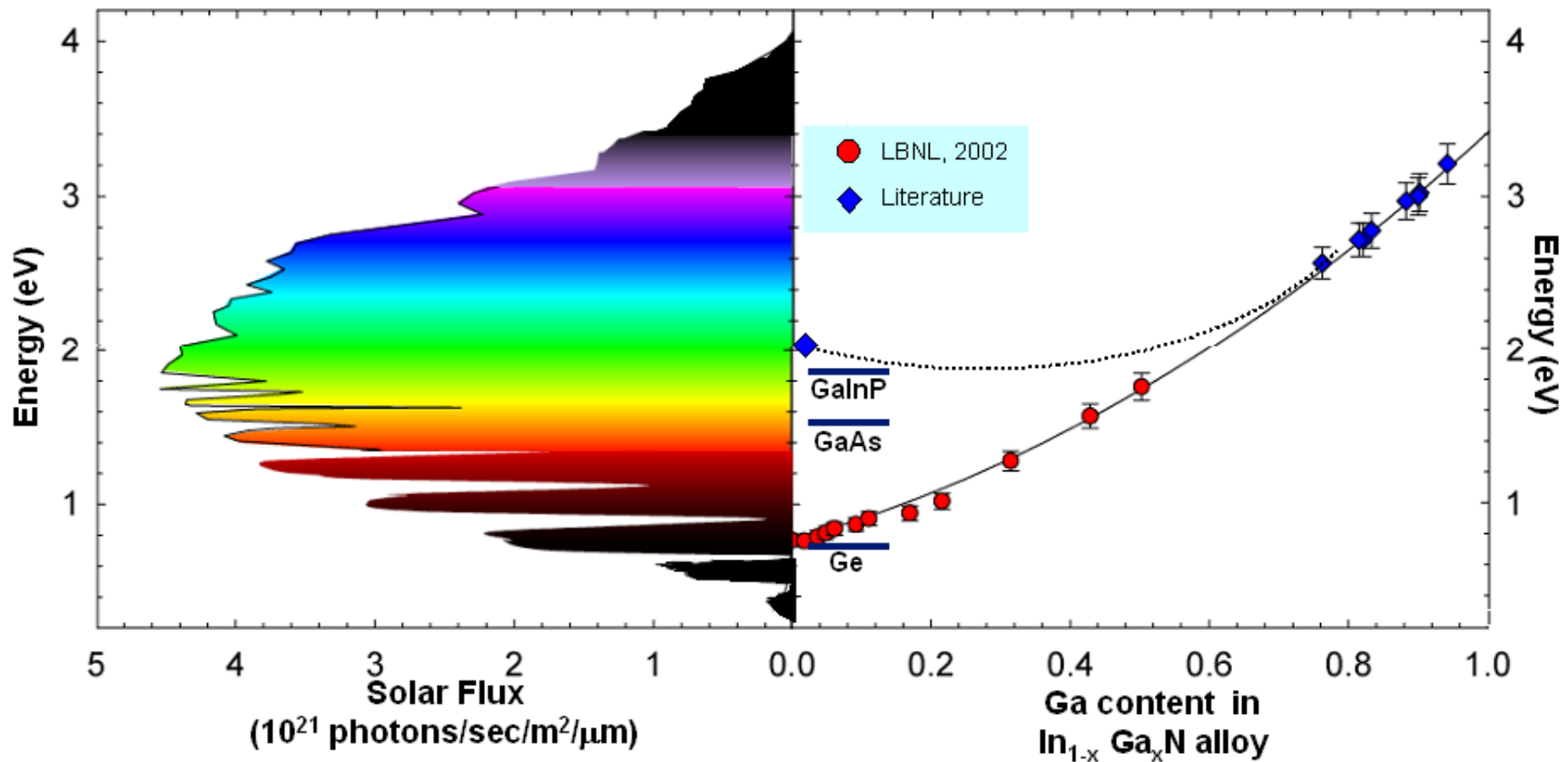


Calculated Dependence of Diffusion Barrier on Strain



Controlled Composition Profiles: tuning the color

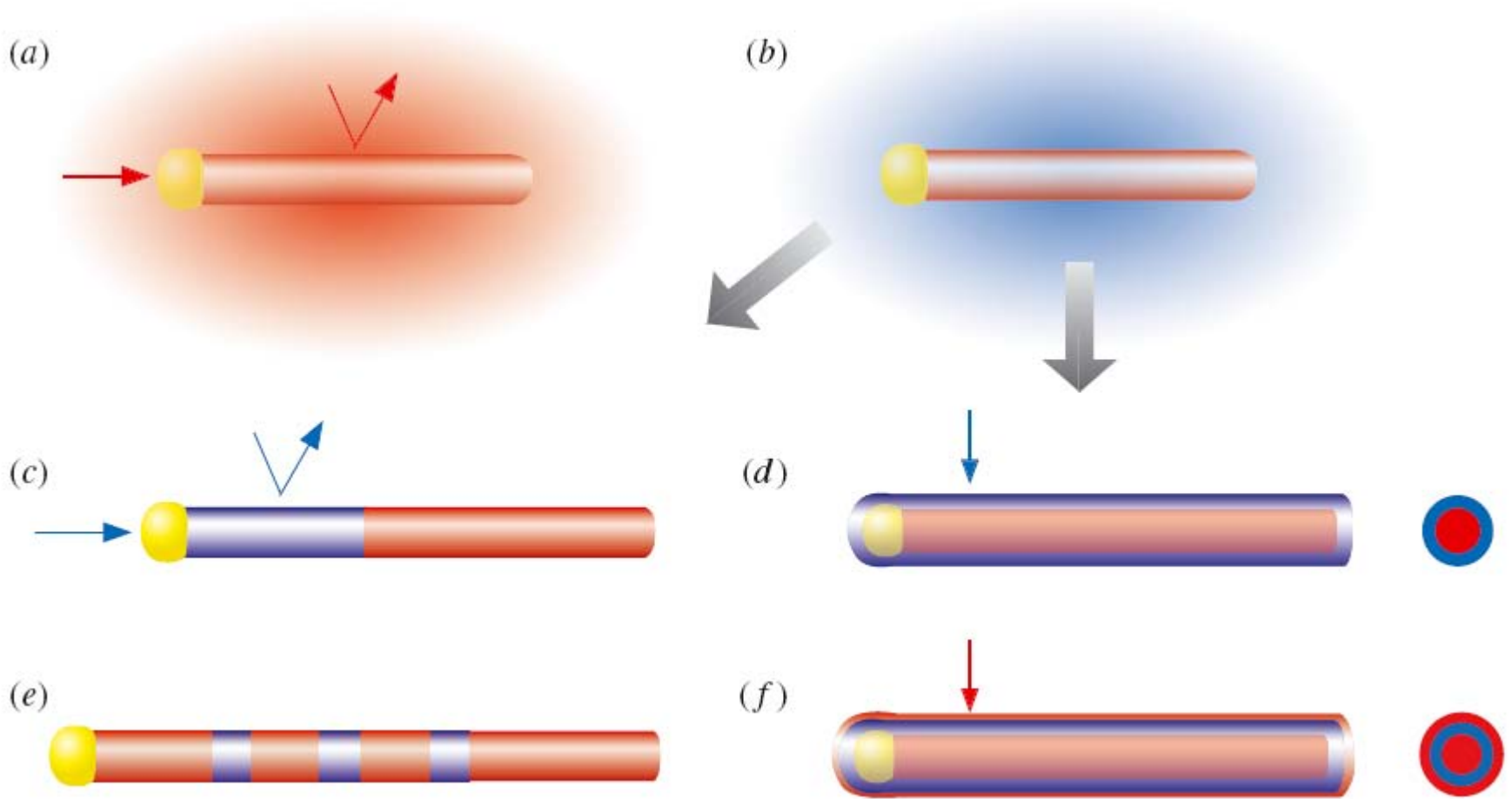
➤ The direct energy gap of $\text{In}_{1-x}\text{Ga}_x\text{N}$ covers most of the solar spectrum



Semiconductor Alloy QDs and NWs: building blocks for nano optoelectronic devices

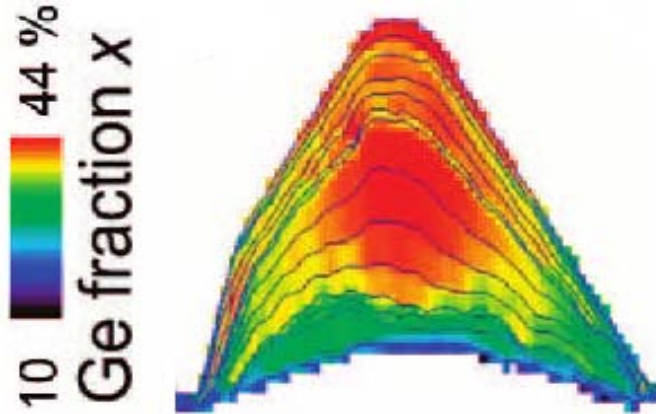


Experiment: sequential growth of axial superlattice and radial core-shell structure of NWs:

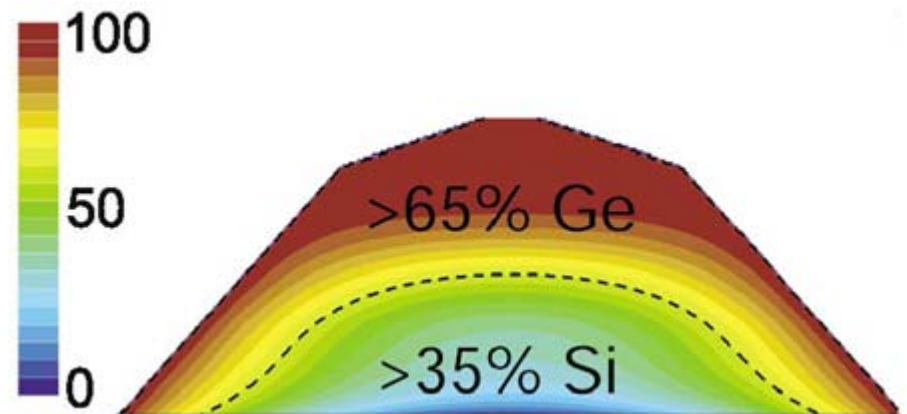


Experiment: self-assembled core-shell QDs & NWs

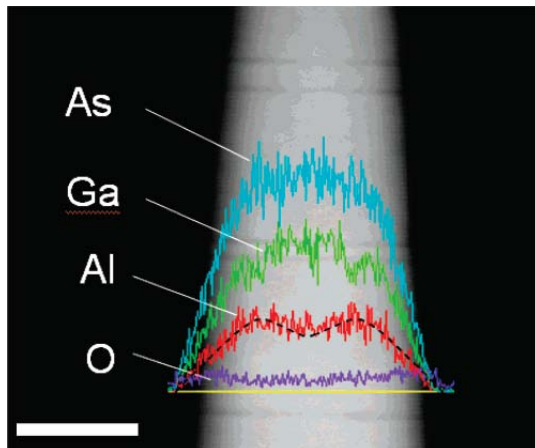
GeSi core-shell QD grown on Si with Ge rich core



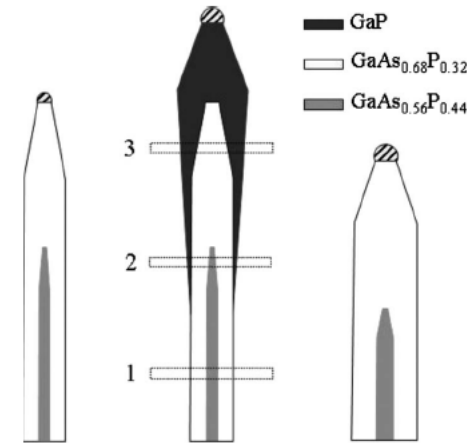
GeSi core-shell QD grown on Si with Si rich core



AlGaAs core-shell NW grown on GaAs with Ga rich core

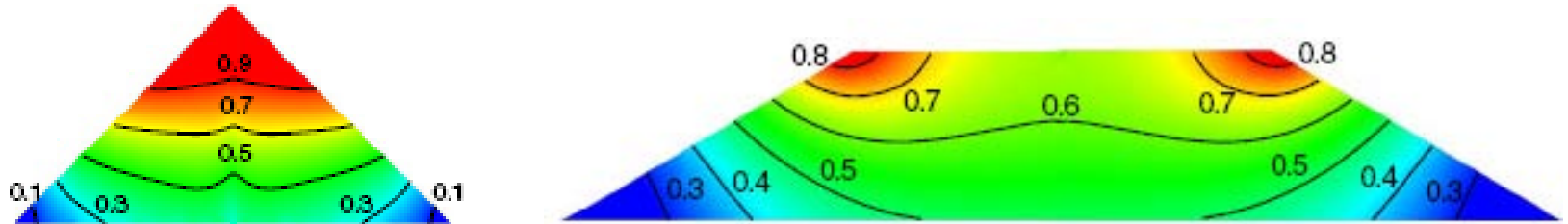


GaAsP core-shell NW grown on Si with P rich core

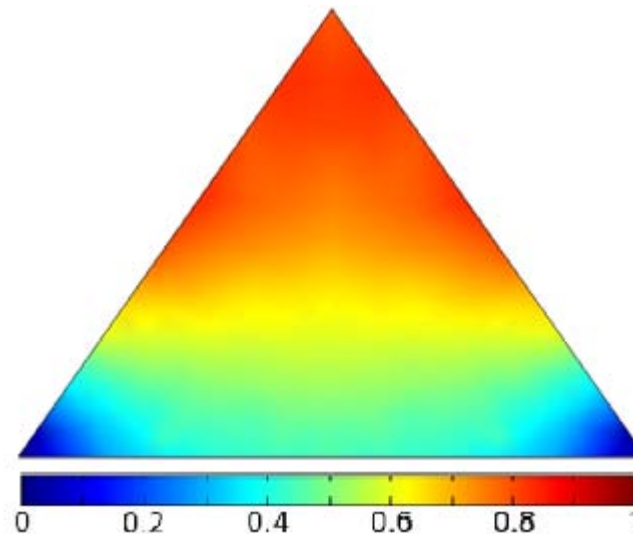


Rastelli, *et al.*, *Nano Letters*, **8**, 1404 (2008); Malachias, *et al.*, *PRL*, **91**, 176101 (2003);
Chen, *et al.*, *Nano Letters*, **7**, 2584 (2007); Mohseni, *et al.*, *JAP*, **106**, 124306 (2009).

Theory: “equilibrium” composition profile



Finite Element result of equilibrium composition profiles in $A_{0.5}B_{0.5}$ QDs
Medhekar, *et. al.*, *Phys. Rev. Lett.* **100**, 106104 (2008);



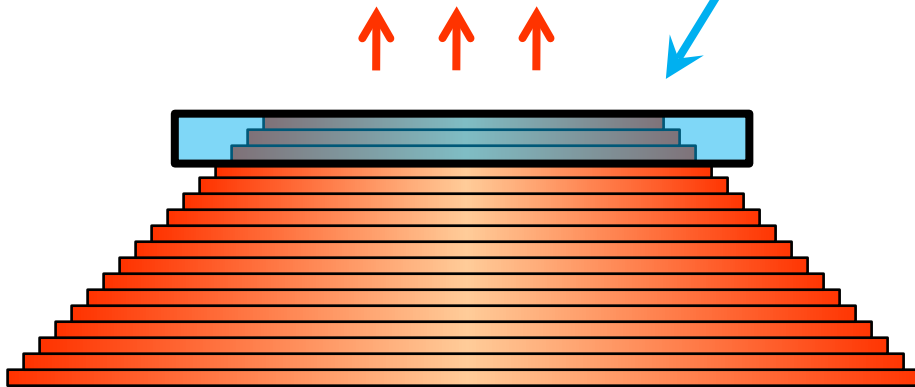
Monte Carlo result of composition profiles in $Ge_{0.6}Si_{0.4}$ QDs
Medhekar, *et. al.*, *Phys. Rev. Lett.* **100**, 106104 (2008);

Motivation: kinetics-limited composition profile

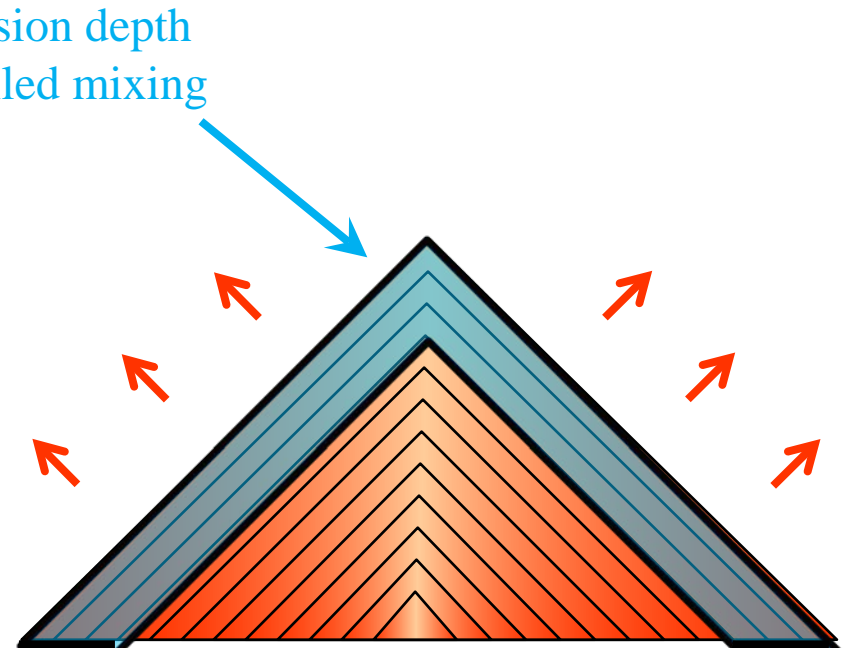
- Composition profile is determined by diffusion limited atom mixing.
- Equilibrium distribution is generally not expected for relatively large nanostructures, while local equilibrium is only established in the surface region (growth front).
 - Surface diffusion \gg Bulk diffusion
- Kinetic growth mode controls the overall composition profile.
 - Layer-by-layer Growth vs. Faceted Growth

Growth Modes: local equilibrium of mixing

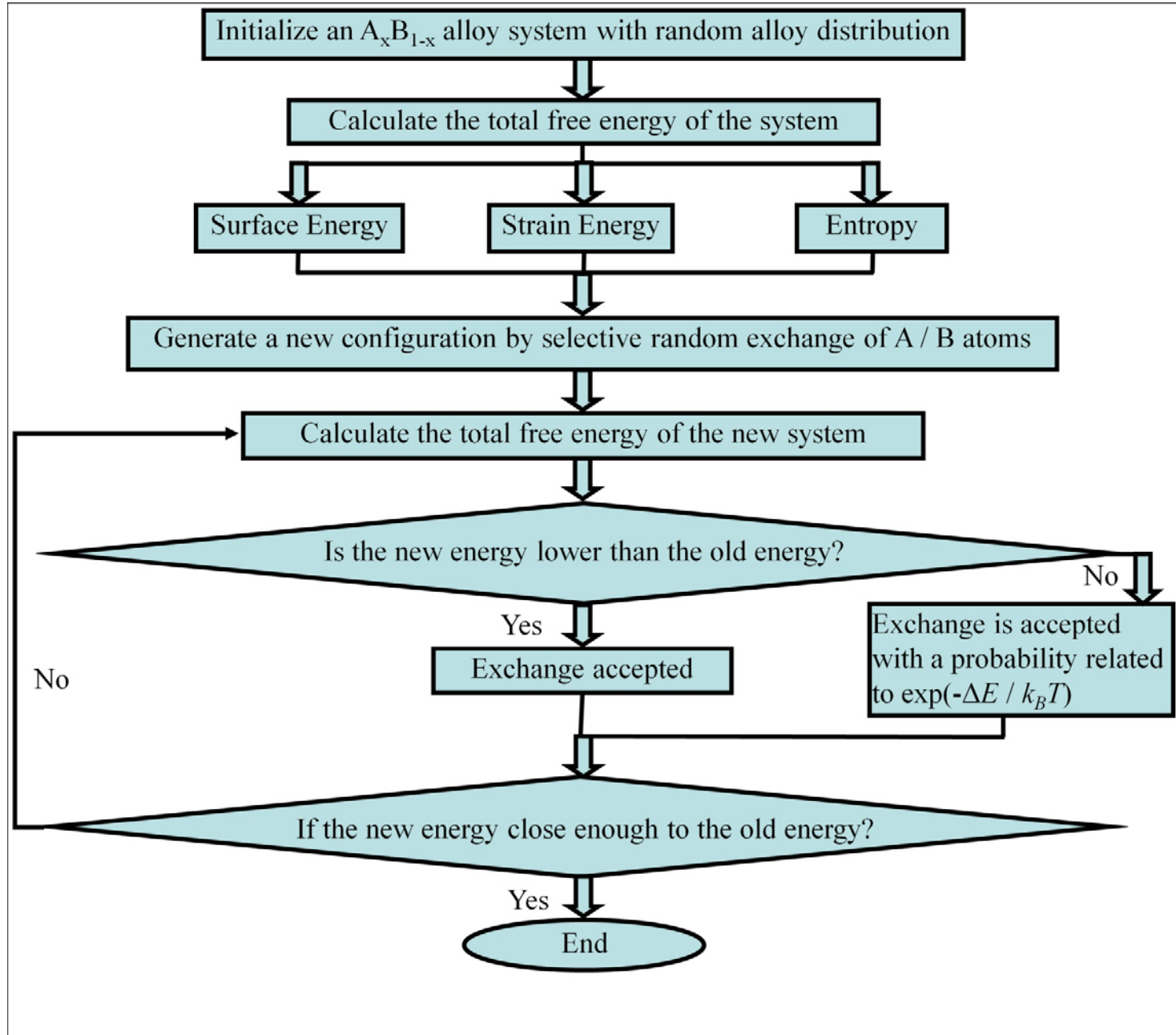
Layer by Layer Growth



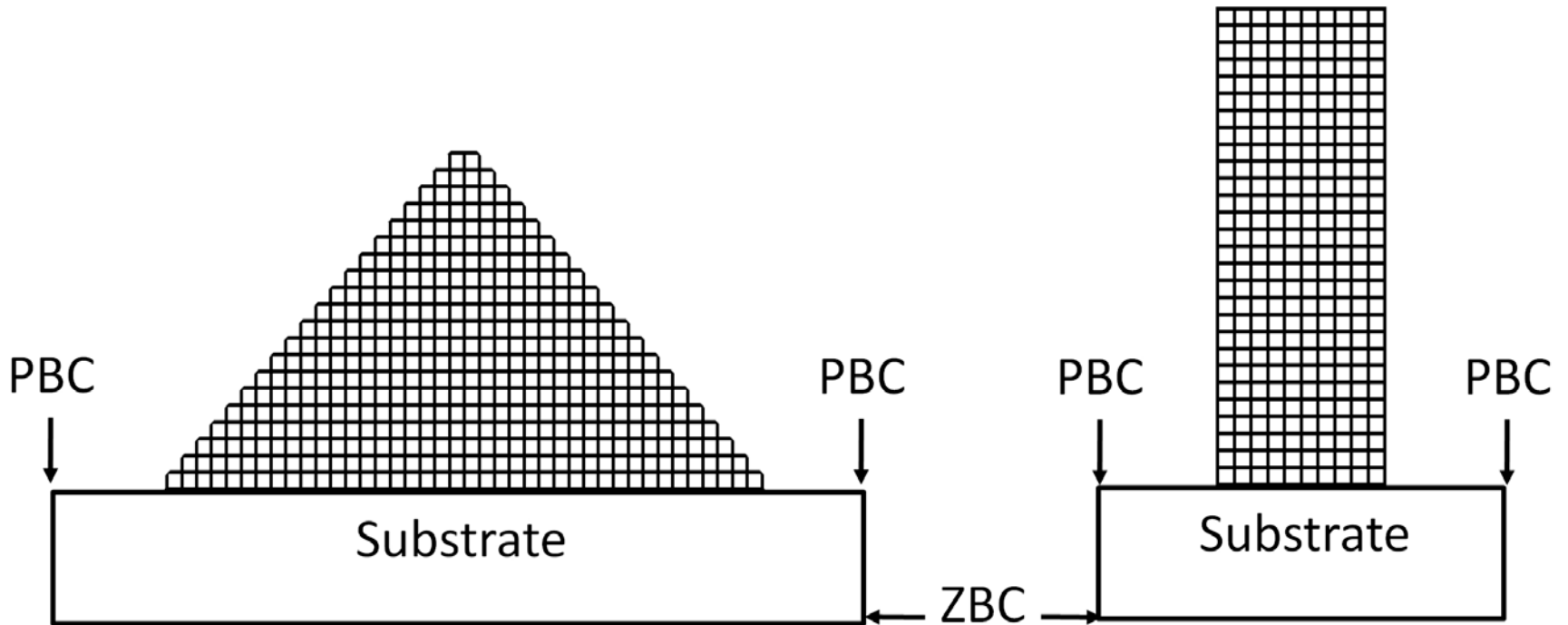
Faceted Growth



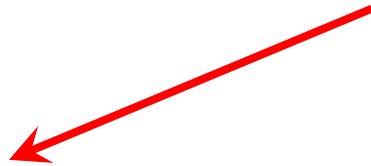
Algorithm of Simulation



Simulation Framework



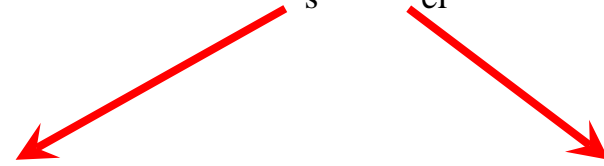
$$G = H - TS,$$



Entropy

Regular solution shell model

$$H = E_s + E_{el}$$



Surface energy

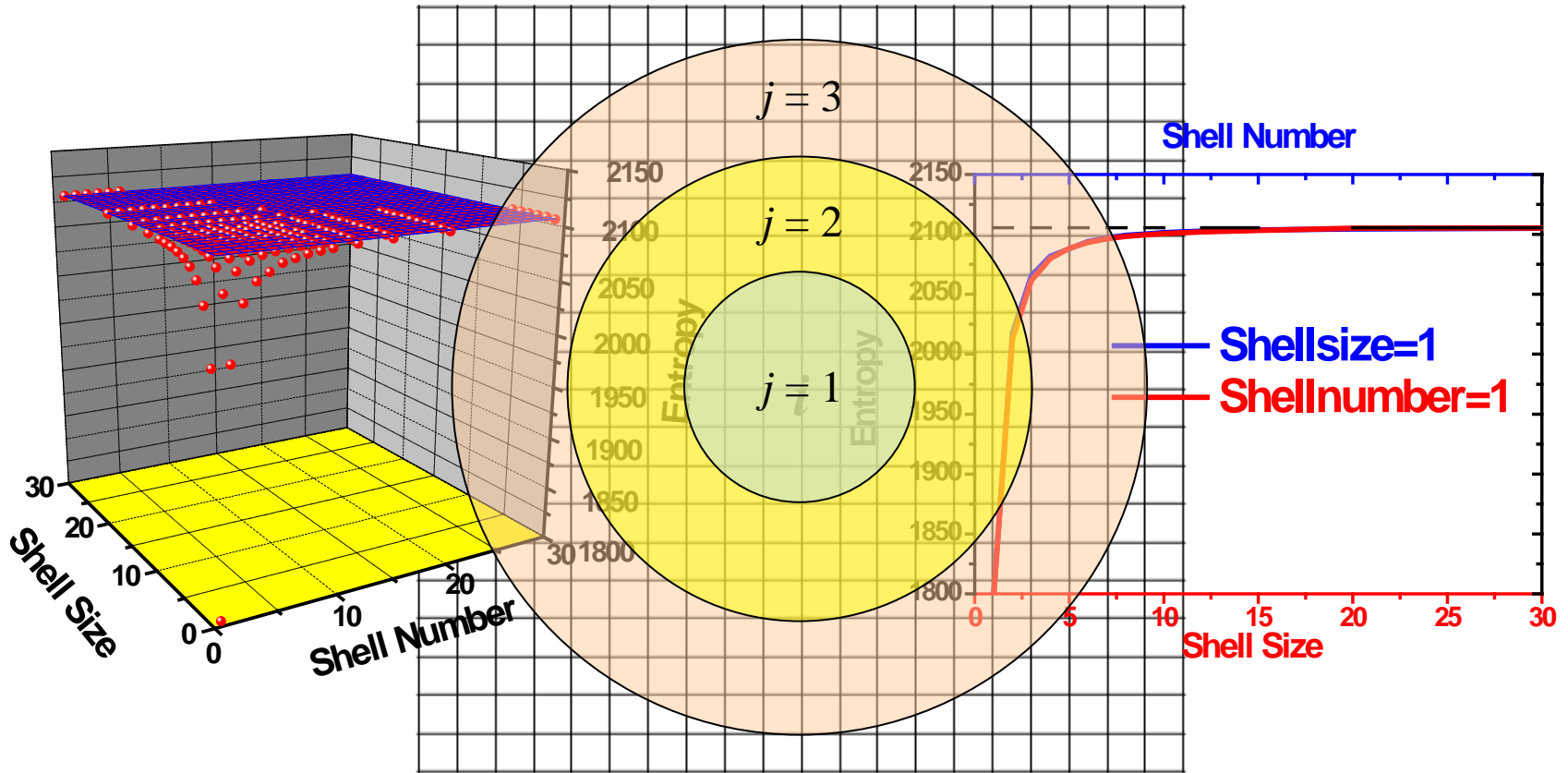
Bond-breaking model

Elastic energy

Atomistic strain Model

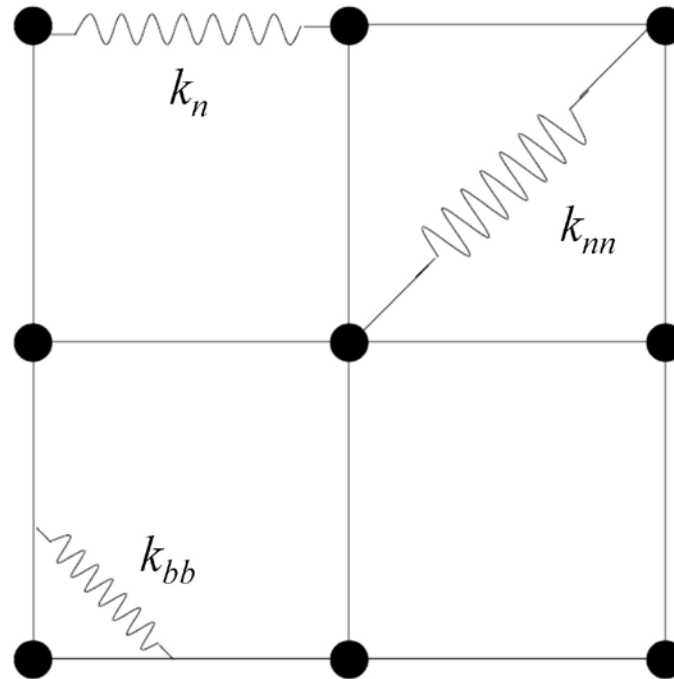
Entropy: regular solution shell model

$$S = \sum_{\text{Lattice } i=1}^N S_i = -k \sum_{\text{Lattice } i=1}^N \left\{ \frac{1}{n} \sum_{\text{Shell } j=1}^n \left[x_{ij} \ln(x_{ij}) + (1-x_{ij}) \ln(1-x_{ij}) \right] \right\}$$



Shell # = 3, Shell Size = 3

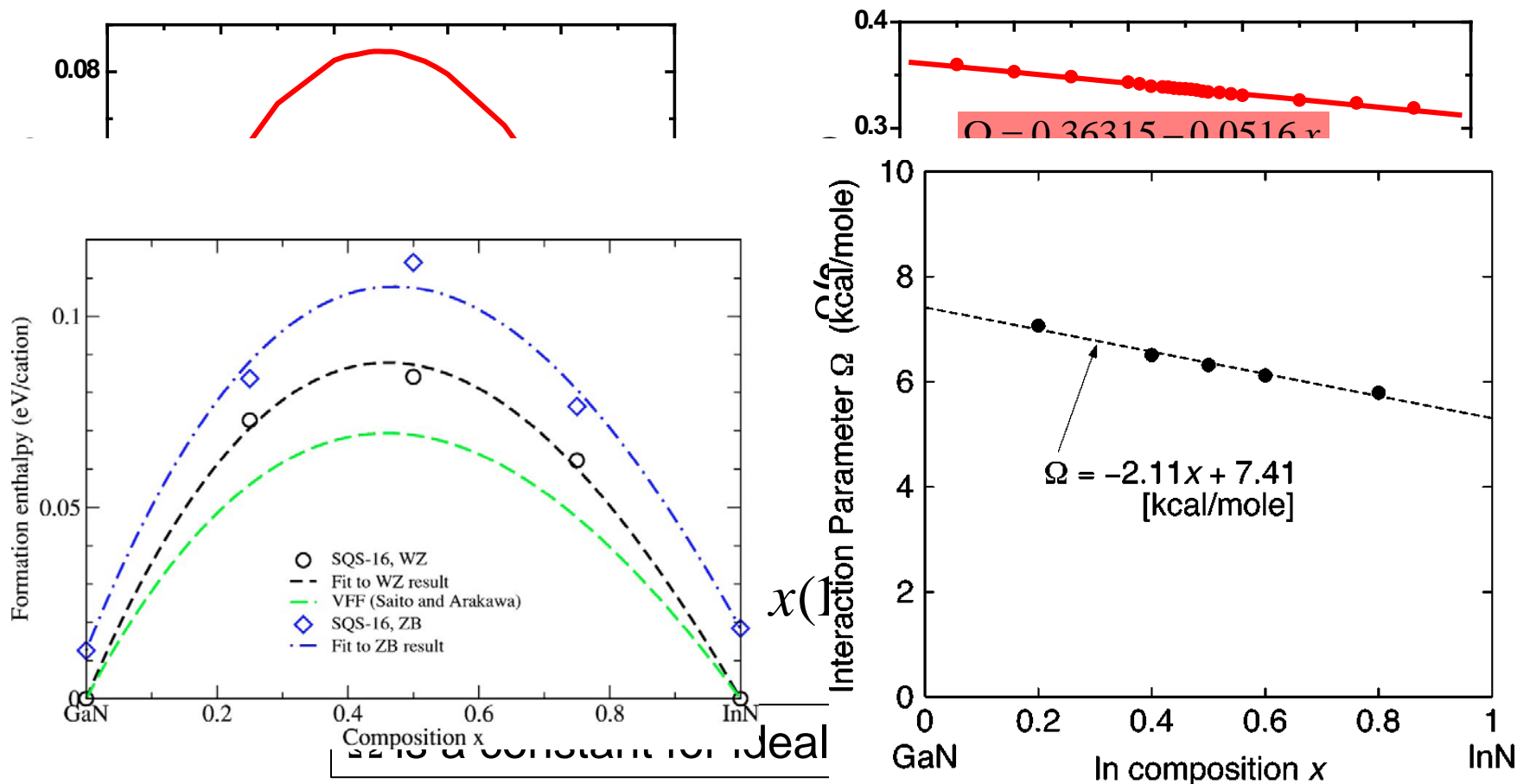
Strain Energy: atomistic stain model



$$E_{el} = k_n (S_{xx}^2 + S_{yy}^2) + k_{nn} \left[(S_{xx} + 2S_{xy} + S_{yy})^2 + (S_{xx} - 2S_{xy} + S_{yy})^2 \right] + k_{bb} S_{xy}^2,$$

$$S_{kl} = \frac{1}{2} (\partial_k u_l + \partial_l u_k), \quad \partial E_{el} / \partial \mathbf{u} = 0, \quad \mathbf{u} \text{ is the displacement vector.}$$

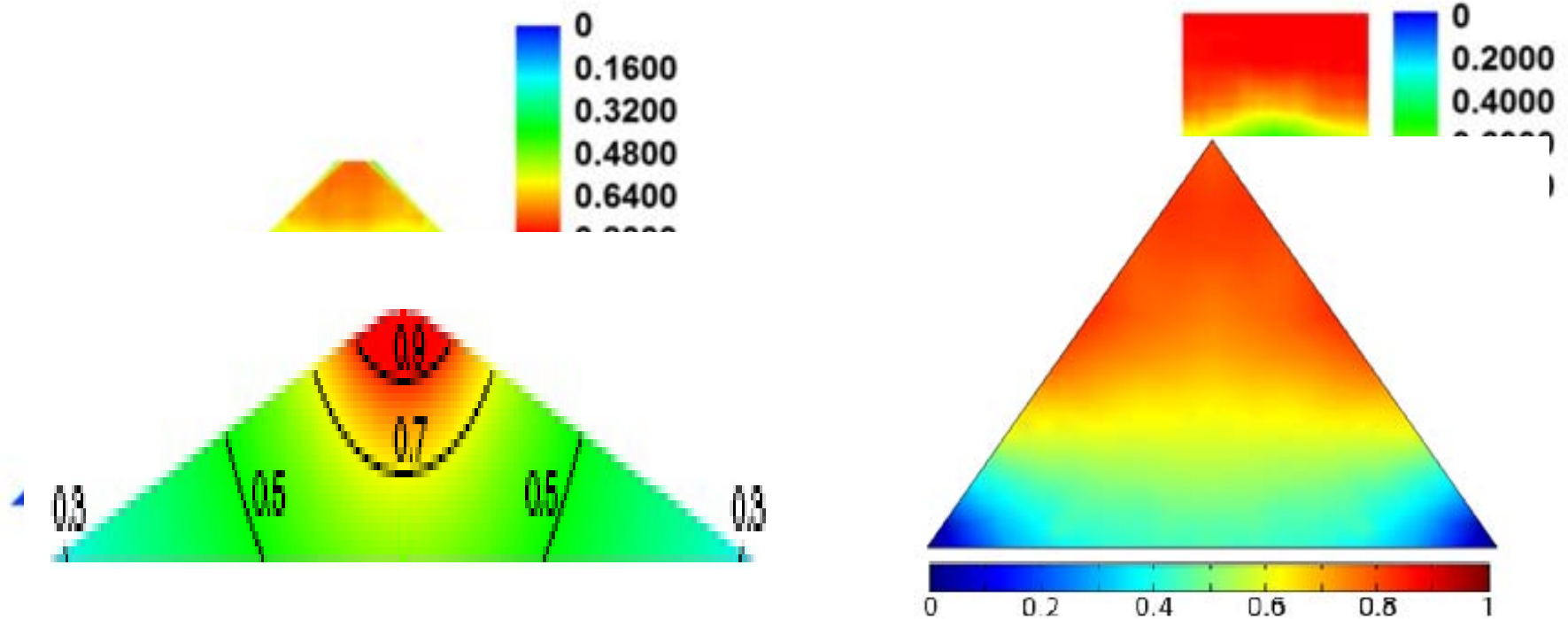
Formation Enthalpy and Interaction Parameter atomistic stain model



Gan, *et al.*, *Phy. Rev. B* **73**, 235214 (2006); Saito, *et al.*, *Phy. Rev. B* **60**, 1701 (1999)

Equilibrium Composition Profile

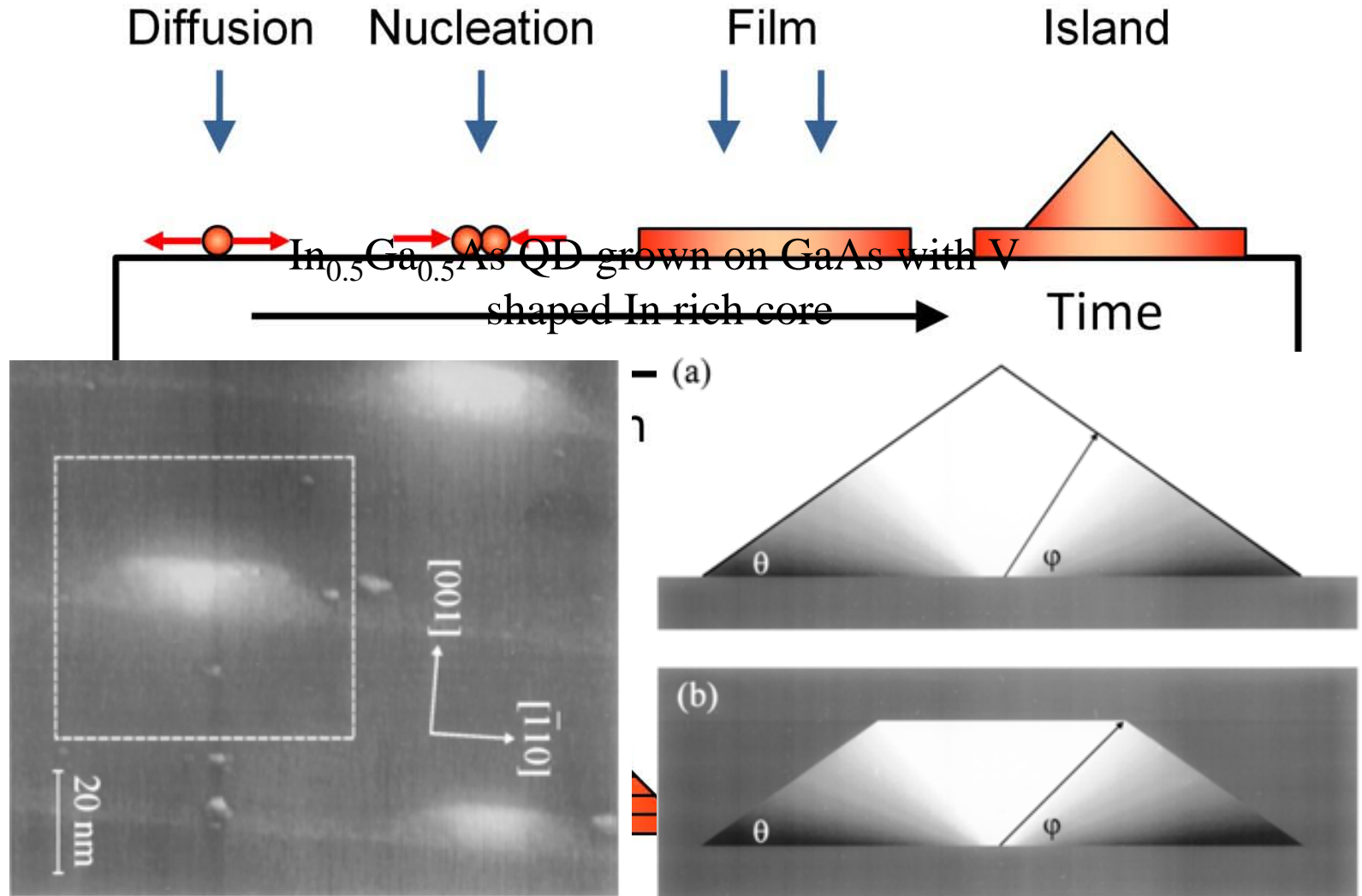
$\text{In}_{0.3}\text{Ga}_{0.7}\text{N}$ QDs and NWs on GaN substrate



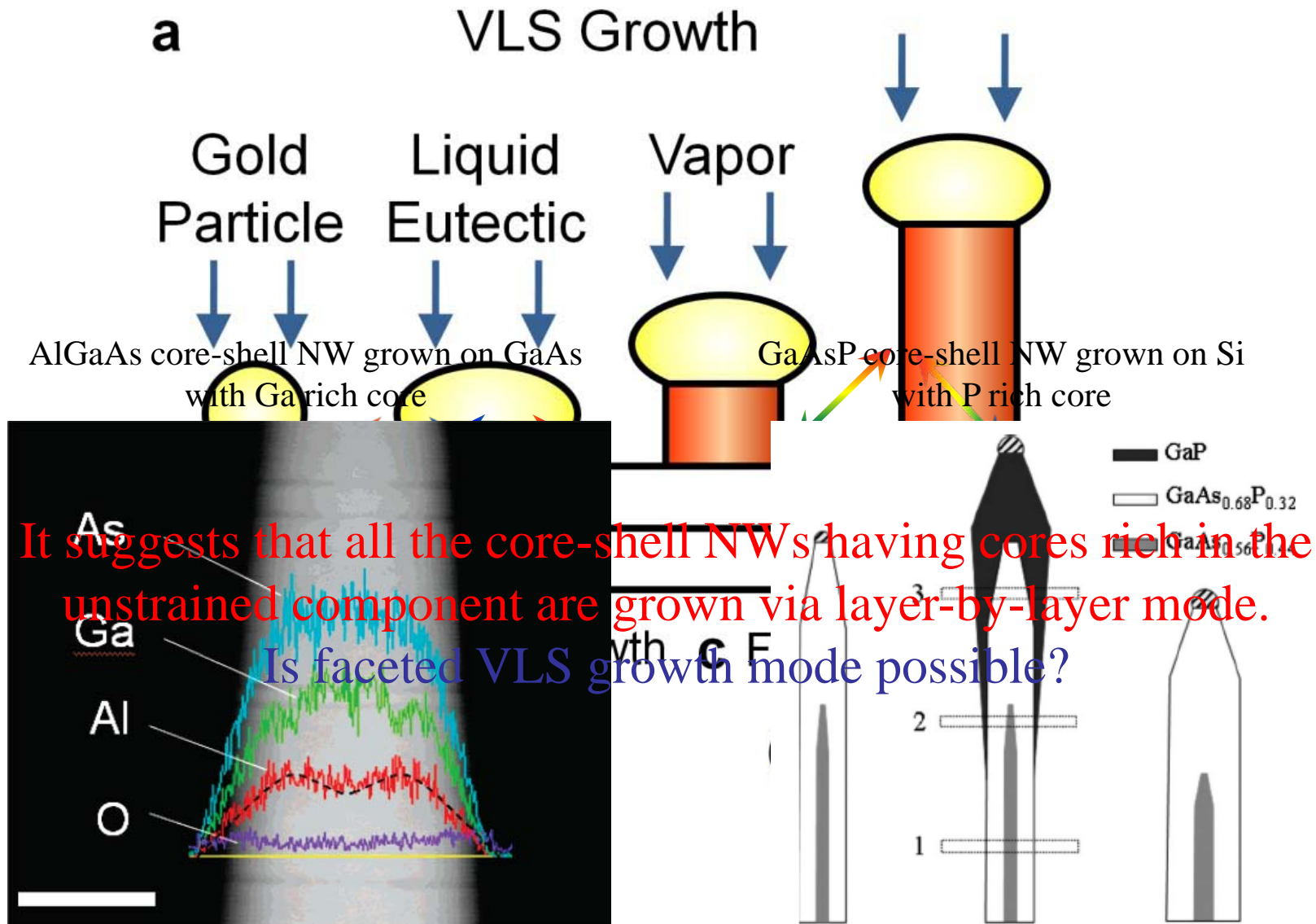
Medhekar, *et. al.*, *Phys. Rev. Lett.* **100**, 106104 (2008);

Uhlík *et. al.*, *J. Phys.: Condens. Matter* **21**, 084217 (2009).

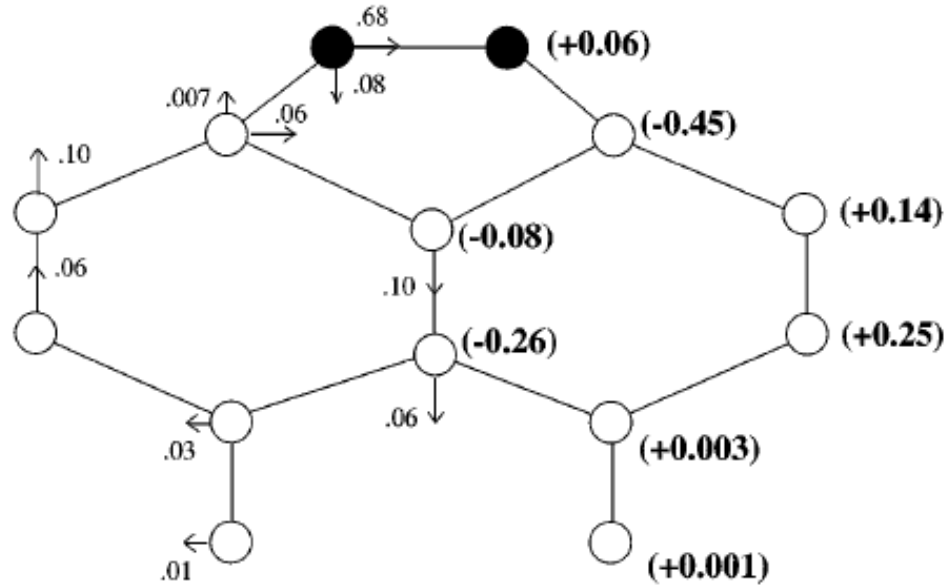
Kinetic Composition Profile of $\text{In}_{0.3}\text{Ga}_{0.7}\text{N}$ QDs



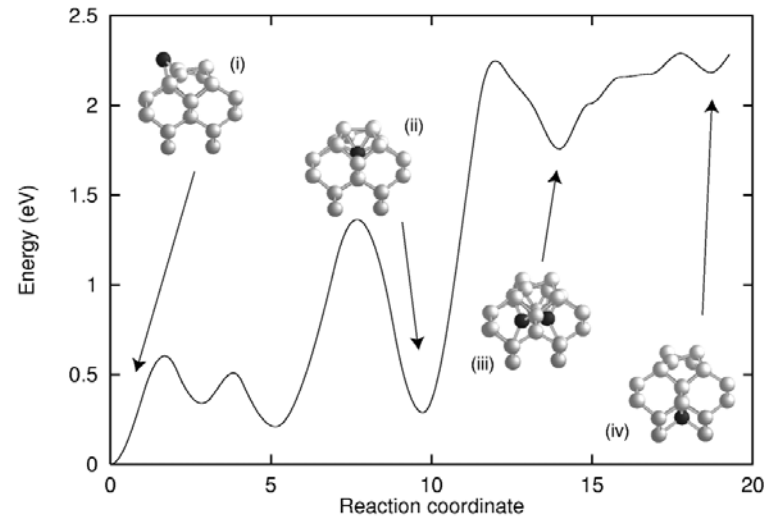
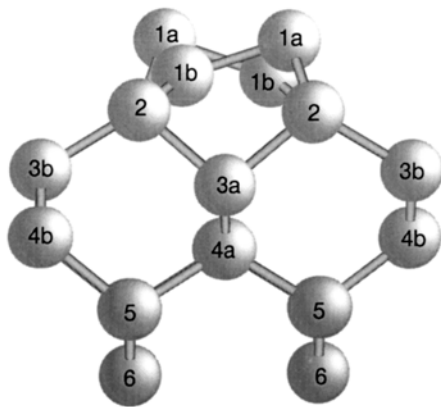
Kinetic Composition Profiles of $\text{In}_{0.3}\text{Ga}_{0.7}\text{N}$ NWs



Diffusion Depth up to Several Sub-Surface Layers

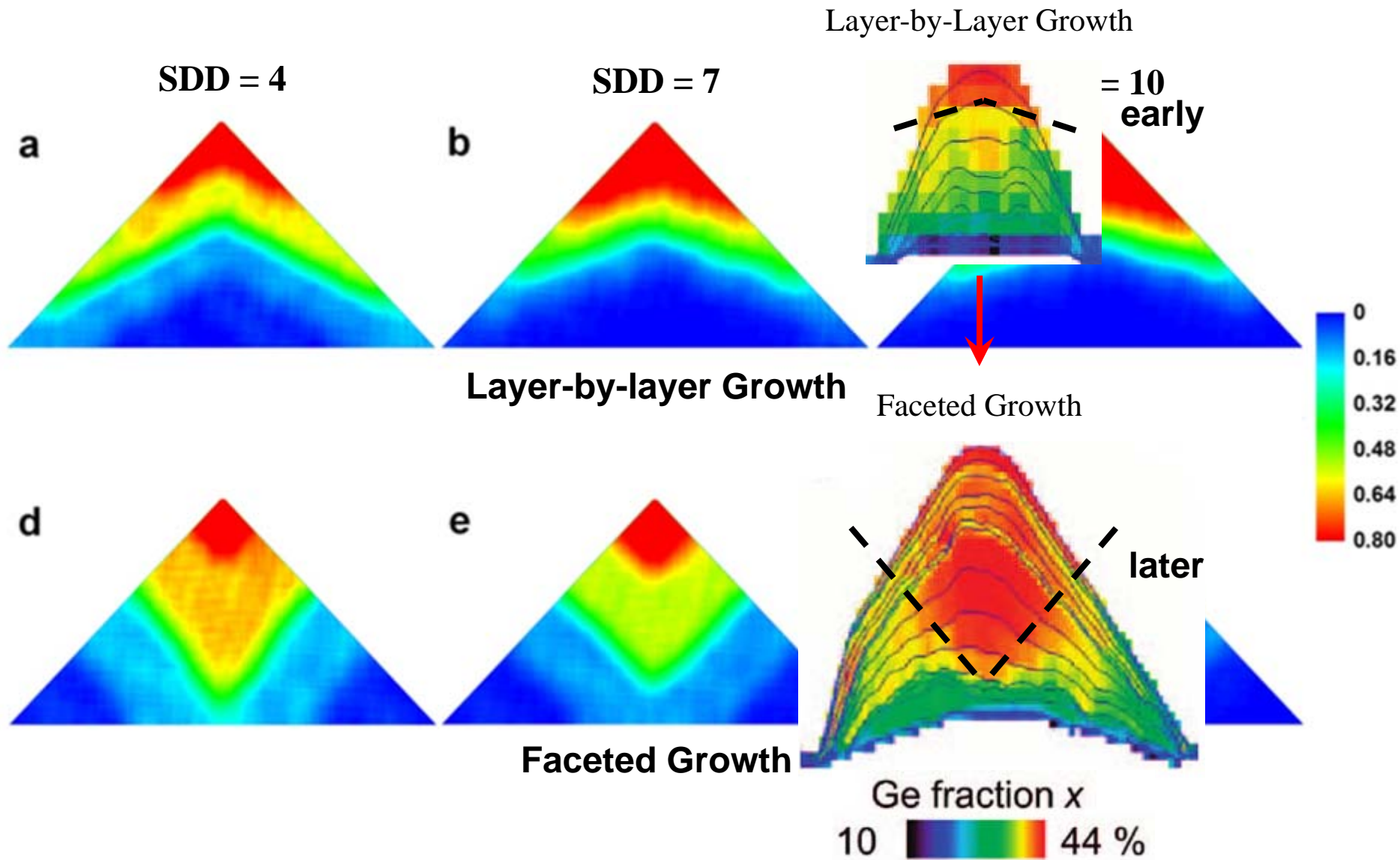


Liu & Lagally, *Phys. Rev. Lett.* 76, 3156 (1996).



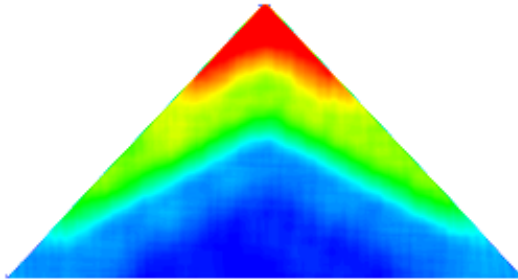
Uberuaga, *et al.*, *Phys. Rev. Lett.* **84**, 2441 (2000).

The Effect of Sub-Surface Diffusion Depth

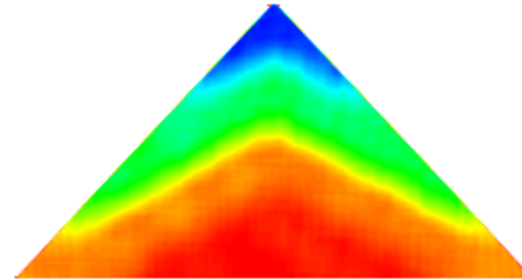


The Effect of Substrate on Alloy Phase Separation reversing the composition – InGaP (SDD=4)

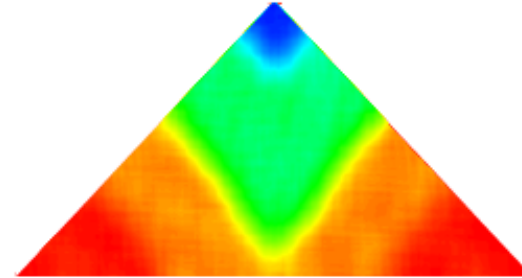
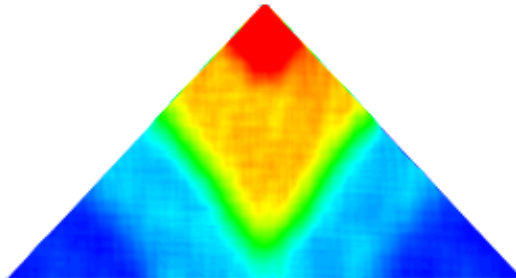
$\text{In}_{0.3}\text{Ga}_{0.7}\text{P}$ on GaP



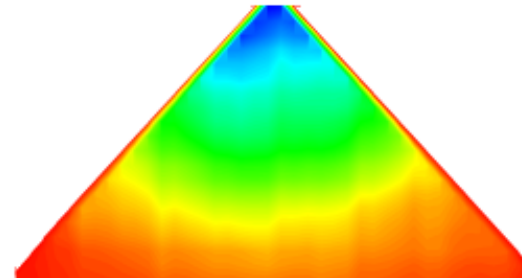
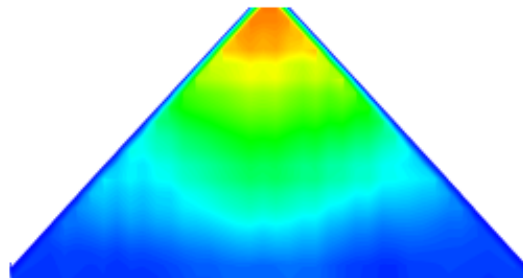
$\text{In}_{0.7}\text{Ga}_{0.3}\text{P}$ on InP



Layer-by-layer Growth



Faceted Growth

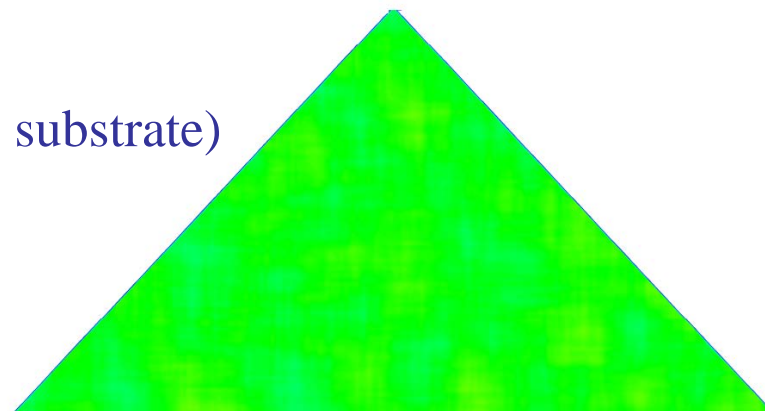
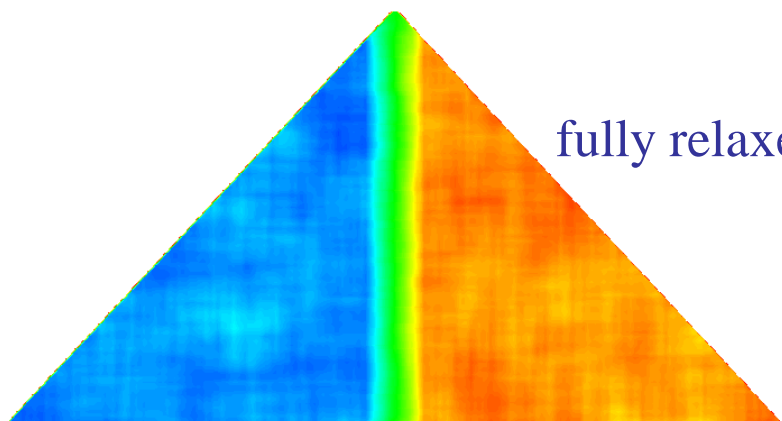


Equilibrium

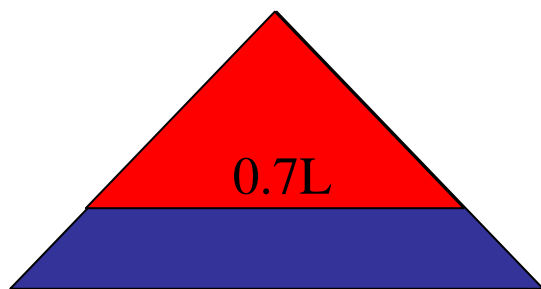
Suppressing Miscibility Gap by Growth

$\text{In}_{0.5}\text{Ga}_{0.5}\text{N}$ with miscibility gap

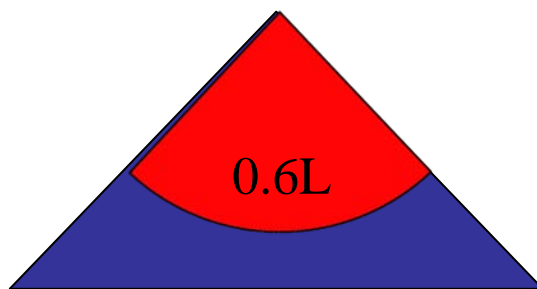
$\text{Ge}_{0.5}\text{Si}_{0.5}$ with no (small) miscibility gap



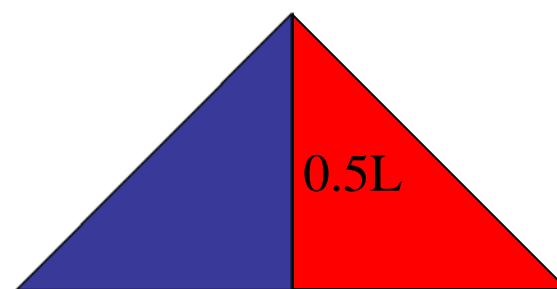
fully relaxed (no substrate)



L



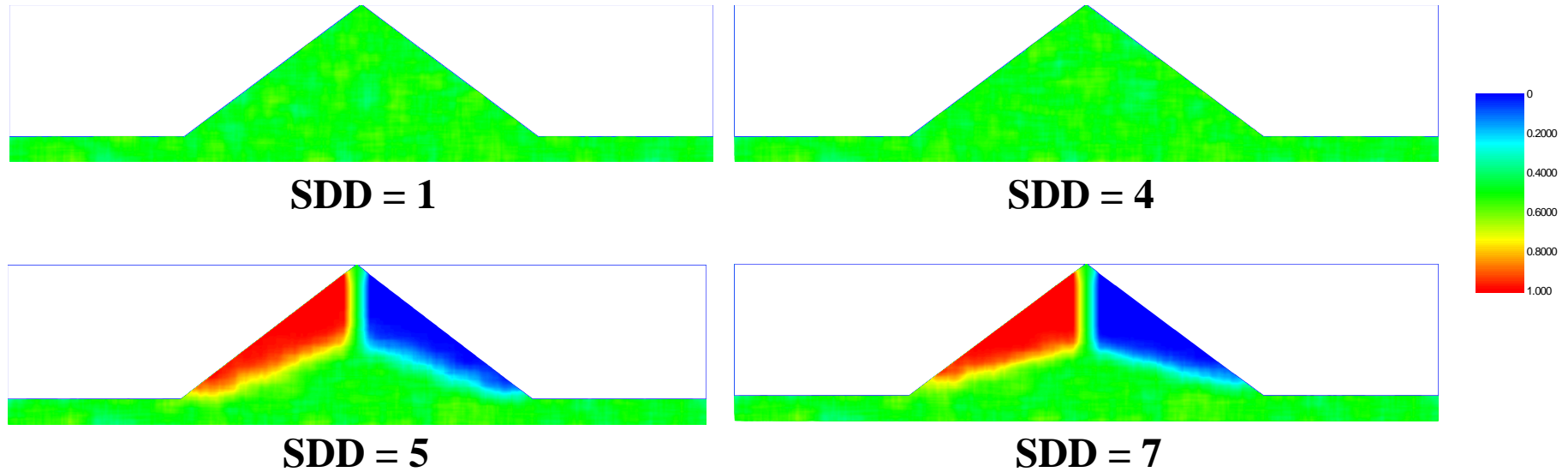
L



L

Suppressing Miscibility Gap by Growth Kinetics

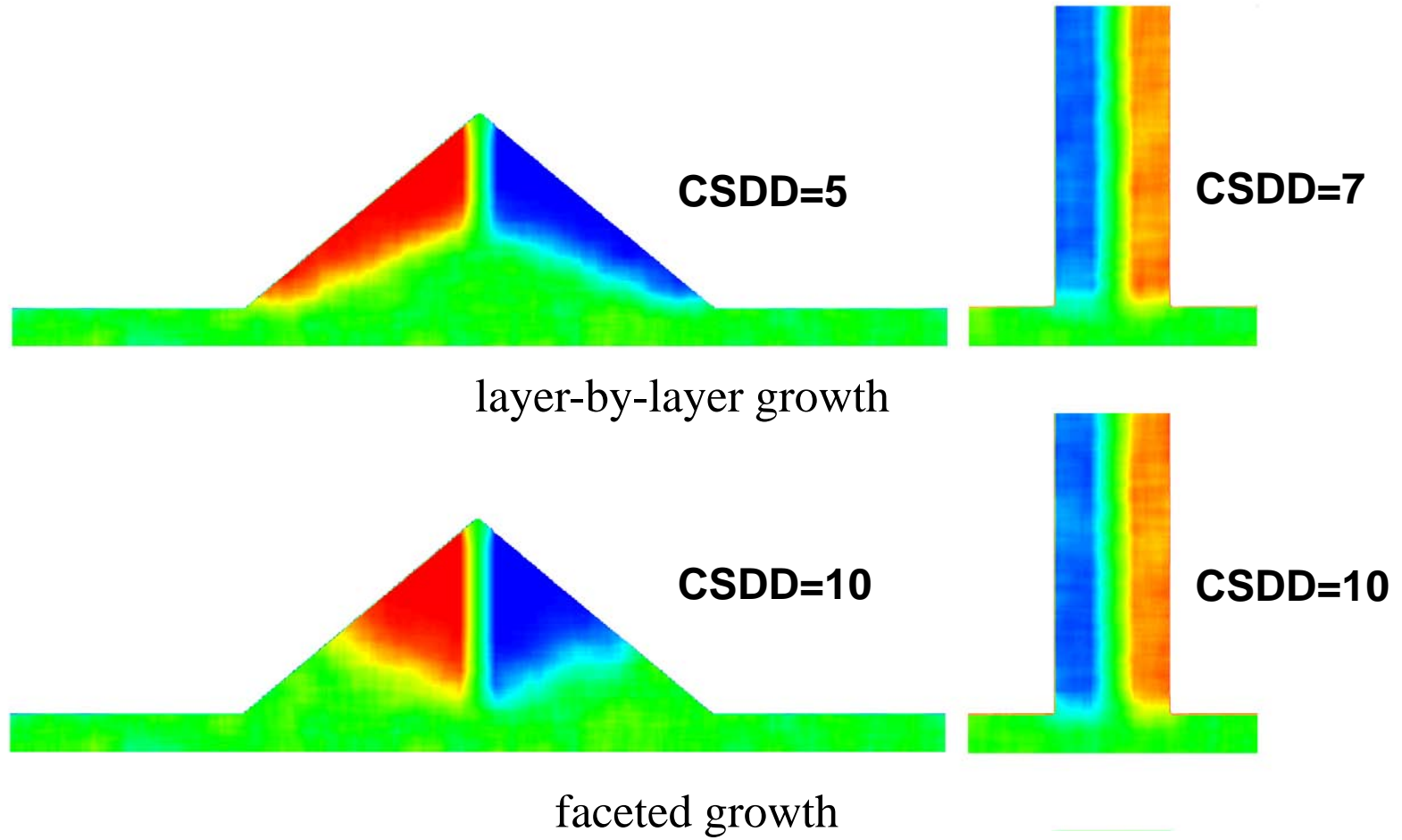
layer-by-layer growth of $\text{In}_{0.5}\text{Ga}_{0.5}\text{N}$ QD on $\text{In}_{0.5}\text{Ga}_{0.5}\text{N}$ substrate



**Critical surface diffusion depth (CSDD) for mixing = 5
(misfit strain acts against phase separation)**

Suppressing Miscibility Gap by Growth Kinetics

the effect of growth mode



Summary

- **The kinetics-controlled alloy composition profiles are distinctively different from the equilibrium composition profiles.**
- **There exists a striking correlation between the composition profiles of epitaxial strained semiconductor alloy QDs and NWs and the growth mode: layer-by-layer versus faceted.**
- **The layer-by-layer growth yields structures with cores rich in the unstrained component by lateral phase separation via strain relaxation; while the faceted growth mode yields structures with cores rich in the strained component by vertical phase separation via strain relaxation.**
- **Suppressing phase separation by selective growth substrate and kinetics**